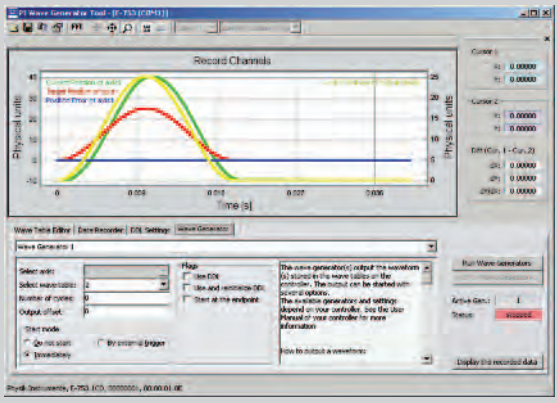
Piezo Stages for Superresolution Microscopy

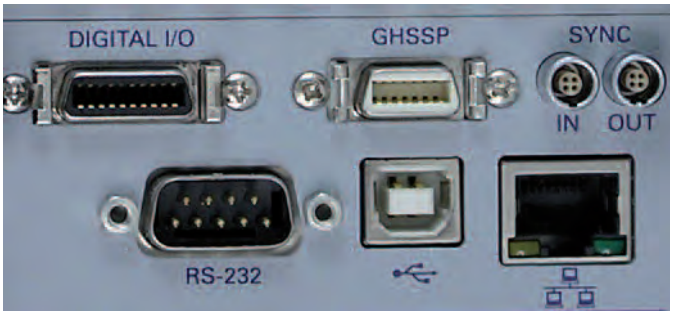
Piezo Systems, Parallel Kinematics, Fast Response, High Stability

Digital Piezo Control improves Performance of SR Microscope Stages

Trajectory Storage, Data Recorder, Macros, System Recognition, Autofocus…



Data recorder and wave generator are part of the MikroMove® software for all digital controllers.



PI controllers are available with a number of different interfaces for highest flexibility. In addition to the modern Ethernet (TCP/IP) and USB, many industrial customers still appreciate the robust RS-232 protocol.

Autofocus

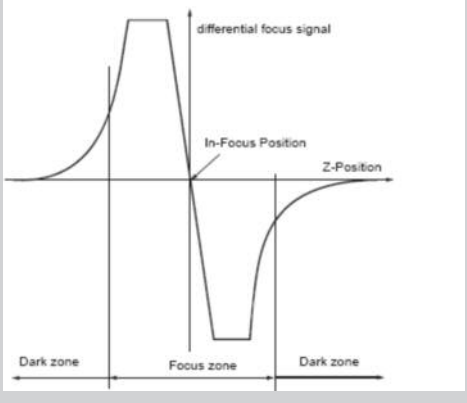
Autofocus routines stored in the firmware allow a function to be implemented which regulates according to an external sensor signal – on the signal output of a vision system, for example. The underlying zero transition method regulates towards a voltage of 0 V at the analog input of the digital controller. This must be able to perform the autofocus routine and have an analog control input.

The autofocus algorithms are possible as standard functions for the E-753 (1 channel), E-725 (3 channels) and E-712 (up to 6 channels) nanopositioning controllers.

ID-Chip Recognition for Automatic Adaptation of the Controllers to the Piezomechanics

The best results for the positional accuracy (linearity) of the piezo system are achieved by adapting various operating parameters. These depend on the individual stage. If digital electronics are tuned once, these parameters are stored in the ID-Chip of the stage. They are therefore automatically available again for the operation at a different digital controller, without the need for an adaptation. This exchangeability between stage and controller is a significant step forward for the flexible use of the systems.

ID-Chip recognition is performed in all E-753, E-725 and E-712 nanopositioning controllers.



Autofocus with the zero transition method: If the control signal is zero, the position is stably maintained. Possible drifts, which lead to a change of the input signal, can be compensated in this way.

Data Recorder: Data Acquisition and Output

The flexibly configurable data recorder enables simultaneous recording and read-out of input and output signals, such as for sensor positions or control voltages depending on time stamps or using trigger signals.

Wave and Profile Generator: Pre-Defined and Programmable Trajectory Profiles

Trajectory profiles of arbitrary, user-defined mathematical functions enable complex 2-axis motion. Depending on the controller used, either time and position data value pairs can be saved (Wave Generator) or complete trajectory profiles with velocity, acceleration and jerk (rate of change of acceleration) can be specified (Profile Generator). The functionality includes:

- Programming of complex functions
- Quick access to common functions (e. g. sine, ramps, triangle and square waves ...)
- Coordination of two axes, e. g. for applications requiring circular motion
- Saving of defined functions in the controller

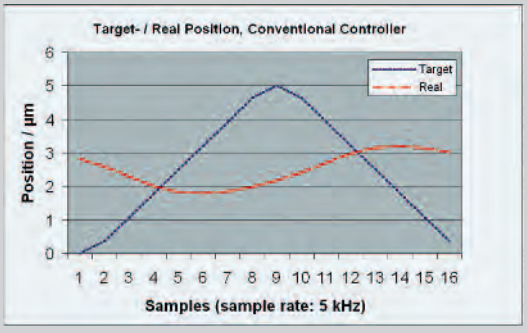
All controller specific functionalities are available as DLL function calls and LabVIEW VIs, which enables their simple integration in external programs. Additional graphical user interfaces allow convenient selection and customization.

DDL: Dynamic Digital Linearizatıon

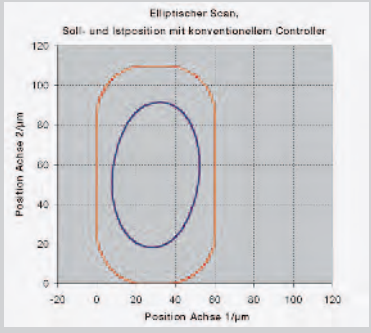
Nanometer Trajectory during Dynamic Scans

Improved Piezo Control: Dynamic Digital Linearization (DDL)

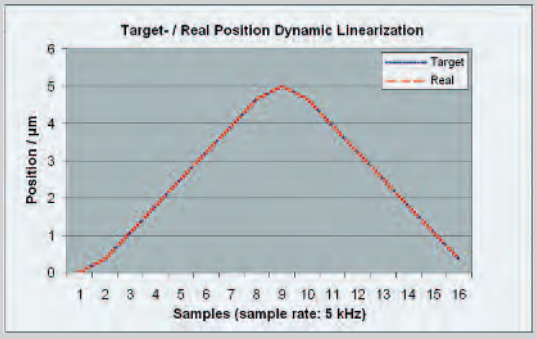
Conventional piezo controllers cannot completely avoid phase-shift and tracking errors in applications with rapid, periodic motion. This is due in part to the non-linear nature of the piezoelectric material, the finite control bandwidth and the inherent limitations of P-I (proportional-integral) servo-control, which only reacts when a position error is detected. The DDL option (ordering number E-710.SCN), available with recent digital piezo controllers such as E-753 (single-channel, see p. 2-108) or E-712 (multi-channel, see p. 2-140), solves this problem. This technology, developed by PI, reduces the error between the current and desired position to imperceptible values. The dynamic linearity and effectively usable bandwidth are thus improved by up to three orders of magnitude. DDL is of benefit to single- and multi-axis applications where motion follows a given trajectory repeatedly (see measurement curves).



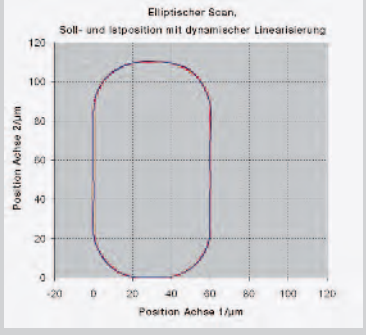
Nanopositioning systems with conventional PID controller: Single axis movement with a 312 Hz triangular signal. The difference between target and actual position can be up to 2.6 µm.



Elliptical scan with a XY piezo scanner and conventional P-I-servo controller. The outer curve shows the desired position, the inner curve shows the actual motion.



Nanopositioning system with DDL option: The same single axis movement as above, with 312 Hz triangular signal. The difference between target and actual position is practically unobservable and is about 7 nanometers.



The same scan as before but with a DDL controller. The tracking error is reduced to a few nanometers, desired and actual position cannot be distinguished in the graph.

E-712 Advanced Digital Nanopositioning Controller

Ideal for High Stability Optical Trapping

Example for the modular use of an E-712 for the vertical and tilt system with three mixed, hybrid drives. They consist of NEXLINE® linear actuators with additional PICMA® actuators for an increased fine adjustment range.

The E-712 digital piezo controller is ideal when it comes to meeting the most demanding accuracy and dynamic-performance requirements of multi-axis nanopositioning systems. The high-performance, real-time operating system makes possible coordinated servo-control of multiple axes (also in parallel-kinematics systems) and thus ensures excellent trajectory control even during complex motion. The modular design allows flexible confection of systems supporting the number of axes and channels required for the application. Flexibility in meeting customers' needs is also behind the interface design: The optional analog inputs and outputs support processing external sensor or control signals as well as driving external amplifiers.

Digital Linearization and Control Algorithms for Highest Accuracy

Linearization algorithms based on higher-order polynomials improve the positioning accuracy to better than 0.01 % for capacitive sensors, typically 10 times better than achievable with conventional controllers.

More than just a Controller — Trajectory Control and Data Recording

During fast periodic motion, as typical for scanning applications, the tracking accuracy can be further improved with Dynamic Digital Linearization (DDL, E-710.SCN). This optionally available control algorithm reduces the tracking error by a factor of up to 1000 and enables the spatial and temporal tracking during a dynamic scan. The integrated wave generator can output periodic motion profiles. In addition to sine and triangle waves, arbitrary, user-defined motion profiles can be created and stored. The flexibly configurable data recorder enables simultaneous recording and read-out of the corresponding data.

Flexible Analog Inputs and Real-time PIO

Each of the four optionally available analog inputs can be configured in two ways. When used as a control input, the applied voltage is linked to one of the axes, for target value settings, for example. When configured as an external sensor input, additional sensor signals e.g. for auto-focusing, can be read in. Alternatively, the system can be equipped with a fast 32-bit PIO (Parallel I/O) for placing commands. The PIO supports a restricted command set required for the motion with 100,000 read and write commands per second.

Simple System Integration

All parameters can be checked and reset via software. System setup and configuration is done with the included NanoCapture™ and PIMikroMove™ user-interface software. Interfacing to custom software is facilitated with included LabVIEW drivers and DLLs. System programming is the same with all PI controllers, so controlling a system with a variety of different controllers is possible without difficulty.

Ordering Information

E-712.3CD
Modular Digital Multi-Channel Piezo Controller, 3 Channels, Capacitive Sensors

E-712.3CDA
Modular Digital Multi-Channel Piezo Controller, 3 Channels, Capacitive Sensors, Analog INs and OUTs

E-712.6CD
Modular Digital Multi-Channel Piezo Controller, 6 Channels, Capacitive Sensors

E-712.6CDA
Modular Digital Multi-Channel Piezo Controller, 6 Channels, Capacitive Sensors, Analog INs and OUTs

These models have RS-232, USB and TCP/IP Interfaces.

Further Interfaces are available:

E-711.IA4
Analog Interface Module, 4 I/O for E-712 modular, digital, Controller System

E-711.IP
PIO Interface Module for E-712 modular, digital, Controller System

Ask about custom designs!

Options and Accessories:

E-710.SCN
DDL (Dynamic Digital Linearization) Firmware Upgrade

E-711.i1B
Analog Cable for Analog I/O, BNC Connector, 1.5 m

E-711.i10
Analog Cable for Analog I/O, Solderable End, 1.5 m

Examples of the modular use of one E-712 for a mixed operation of low voltage and medium voltage actuators (120 V or ±250 V). The positioning system has two separate axis systems for the adjusting and actual measurement process in an inspection system.

Technical Data

Model	E 712.3CD	E 712.6CD	E-712.3CM
Function	Modular digital controller for multi-axis piezo nanopositioning systems with capacitive sensors	Modular digital controller for multi-axis piezo nanopositioning systems with capacitive sensors	Modular digital controller for PicoCube® nanopositioning systems with capacitive sensors
Axes	3	6	3
Processor	PC-based, 600 MHz, real-time operating system	PC-based, 600 MHz, real-time operating system	PC-based, 600 MHz, real-time operating system
Sampling rate, servo-control	50 kHz	20 kHz	50 kHz
Sampling rate, sensor	50 kHz	20 kHz	50 kHz
Sensor			
Servo characteristics	P-I, two notch filters	P-I, two notch filters	P-I, two notch filters
Sensor type	Capacitive	Capacitive	Capacitive
Sensor channels	3	6	3
Sensor bandwidth (-3 dB)	10 kHz	10 kHz	10 kHz
Sensor resolution	18 Bit	18 Bit	18 Bit
Ext. synchronization	Yes	Yes	Yes
Amplifier			
Output voltage	-30 V to +135 V	-30 V to +135 V	-250 V to +250 V
Amplifier channels	4	8	4
Peak output power per channel	25 W	25 W	45 W
Average output power per channel	8 W	8 W	15 W
Peak current	250 mA	250 mA	180 mA
Average current per channel	100 mA	100 mA	60 mA
Current limitation	Short-circuit-proof	Short-circuit-proof	Short-circuit-proof
Resolution DAC	20-bit	20-bit	20-bit
Interfaces and operation			
Communication interfaces	Ethernet, USB, RS-232	Ethernet, USB, RS-232	Ethernet, USB, RS-232
Piezo / sensor connector	Sub-D special connector	Sub-D special connector	Sub-D special connector
Analog in/out	optional je 4 x LEMO, ±10 V (E-711.IA4)	optional je 4 x LEMO, ±10 V (E-711.IA4)	optional je 4 x LEMO, ±10 V (E-711.IA4)
Digital in/out	MDR20; 2 x IN, 8 x OUT; TTL	MDR20; 2 x IN, 8 x OUT; TTL	MDR20; 2 x IN, 8 x OUT; TTL
Command set	PI General Command Set (GCS)	PI General Command Set (GCS)	PI General Command Set (GCS)
User software	NanoCapture™, PIMikroMove®	NanoCapture™, PIMikroMove®	NanoCapture™, PIMikroMove®
Software drivers	LabVIEW Drivers, DLLs	LabVIEW Drivers, DLLs	LabVIEW Drivers, DLLs
Supported functionality	Wave gen, trigger I/O	Wave gen, trigger I/O	Wave gen, trigger I/O
Display	LEDs for OnTarget, Err, Power	LEDs for OnTarget, Err, Power	LEDs for OnTarget, Err, Power
Linearization	4th order polynomials, DDL-Option (Dynamic Digital Linearization)	4th order polynomials, DDL-Option (Dynamic Digital Linearization)	4th order polynomials, DDL-Option (Dynamic Digital Linearization)
Miscellaneous			
Operating temperature range	5 to 50 °C	5 to 50 °C	5 to 50 °C
Overtemp protection	Max. 75°C, of the piezo voltage output	Max. 75°C, deactivation of the piezo voltage output	Max. 75°C, deactivation of the piezo voltage output
Mass	5.35 kg	5.78 kg	5.43 kg
Dimensions	9,5" chassis, 236 x 132 x 296 mm + handles (47 mm length)	9,5" chassis, 236 x 132 x 296 mm + handles (47 mm length)	9,5" chassis, 236 x 132 x 296 mm + handles (47 mm length)
Power consumption	100 W max.	100 W max.	100 W max.
Operating voltage	90 to 240 VAC, 50–60 Hz	90 to 240 VAC, 50–60 Hz	90 to 240 VAC, 50–60 Hz

E-709 Compact and Cost-Optimized Digital Piezo Controller

Increased Performance and Low Cost for SR Microscopy

Compact, low-cost E-709 digital controller (preliminary case design) with P-712 piezo-scanner

- **Fast Digital Controller, Software Configurable Servo Parameters**
- **Linearity of SGS and Piezoresistive Sensors Improved by up to 0.02 %**
- **2 Digital Interfaces: USB, RS-232**
- **Comprehensive I/O Functions**
- **Additional High-Bandwidth Analog Control Input / Sensor Input**
- **Low-Cost OEM Versions Available**
- **Comprehensive Software Package**

The E-709 opens up the possibilities of digital control for piezo-driven nanopositioning systems for the same price as analog controllers. It was designed for piezo actuators and nanopositioning stages which are equipped with cost effective measuring systems such as strain gauges or piezoresistive sensors. The advantage: higher precision, more control options and very simple operation. In addition, PI provides the full functionality of its comprehensive software packages free of charge! The E-709 can also be used for applications providing analog control signals. In addition to 2 digital interfaces, a standard broadband analog input is installed as well.

Digital Linearization for Strain Sensors: 10 x More Precise!

For the first time, the E-709 nanopositioning controller opens up the advantages of digital control to compact systems with strain sensors. These sensors are based on the strain of metal foils or semiconductor films (piezoresistive sensors) and are used when space limitations prevent the use of the more advanced capacitive sensors, or where the requirements in terms of resolution or temperature stability are not as critical.

The limited linearity of these strain sensors can be improved by digital controllers, which use additional linearization algorithms to minimize the deviation between target and actual position. This improves the accuracy by up to one order of magnitude and achieves linearity values of up to 0.02 %.

Flexibility: Software Configurable Servo Parameters

All servo controllers require tuning and adjustment of servo parameters for optimum performance (e.g. as a result of changes to the load or the motion profile). With a digital controller, all adjustments are carried out by simple software commands and the resulting motion or transient characteristics can be viewed, analyzed and further optimized immediately with the provided software. It is also possible to switch between previously found sets of parameters when the controller is in operation. Since jumpers and potentiometers no longer have to be set manually, system integration becomes much more straight forward.

OEM Versions at an Even Lower Price

E-709 controllers are also offered without case. A lower cost version sold as the E-609 is available for purely analog control signals, maintaining the advantages of digital signal processing and parameter setting. The target position is controlled via an analog signal, allowing system components with analog output (e.g. autofocus) to be integrated easily.

An E-709 version for capacitive position sensors is also available to control the large variety of ultra-high precison single-axis nanopositioning systems PI offers.

Ordering Information

E-709.PRG
Digital Piezo Controller, 1 Channel, -30 to 130 V, Piezoresistive Sensors, Bench-Top

E-709.SRG
Digital Piezo Controller, 1 Channel, -30 to 130 V, SGS-Sensor, Bench-Top

E-709.PR
Digital Piezo Controller, 1 Channel, OEM Module, -30 to 130 V, Piezoresistive Sensors

E-709.SR
Digital Piezo Controller, 1 Channel, OEM Module, -30 to 130 V, SGS-Sensor

Accessories

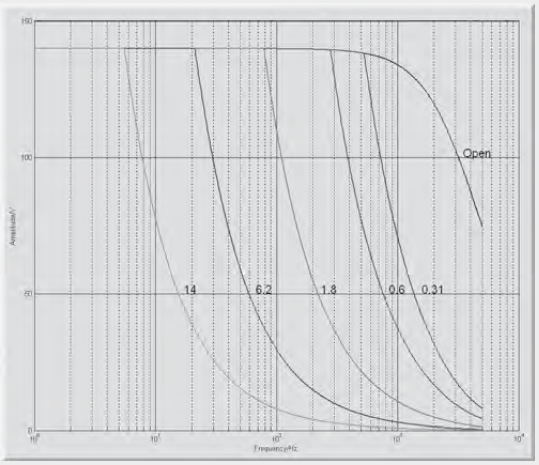
E-709.01
Adapter HD-Sub-D 26-pin to Sub-D 9-pin with I/O Lines, 0.5 m

E-709.02
Adapter Cable HD-Sub-D 26-pin to Open Leads, 1 m

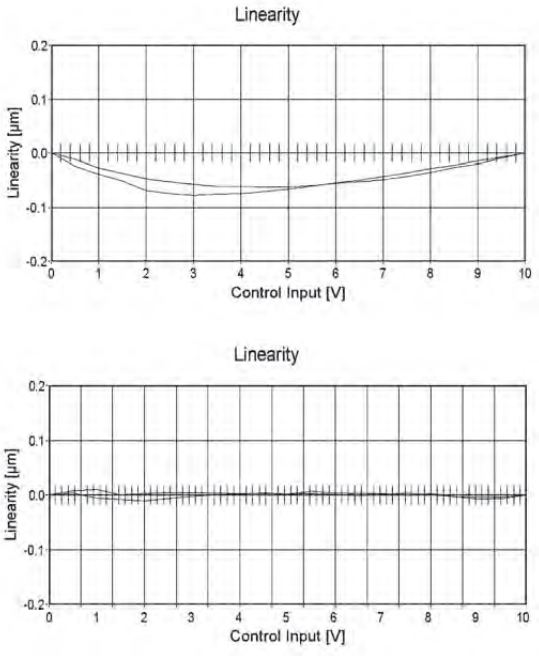
E-709.03
Adapter LEMO to Sub-D 9-pin

The E-709 is also available as a compact, low-cost controller for capacitive sensor-equipped positioning systems.

E-709 OEM Version board



E-709: operating limits with various PZT loads (open-loop), capacitance is measured in µF



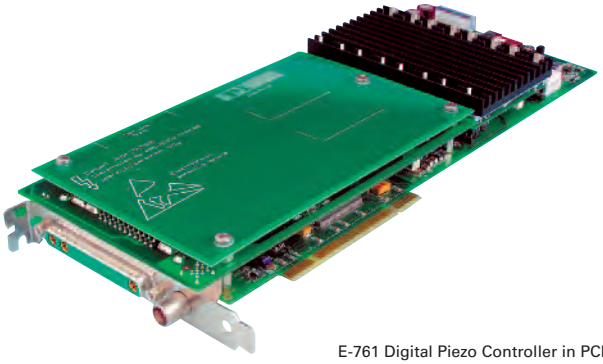
Comparison of the linearity of a strain gauge sensor with analog controller (top) and the E-709 digital controller (bottom), which improves the linearity by up to one order of magnitude

Technical Data

Modell	**E-709.SR E-709.SRG E-709.PR E-709.PRG**
Function	Digital controller for single-axis piezo nanopositioning systems (.SR, .PR: OEM board)
Channels	1
Processor	DSP 32-bit floating point, 150 MHz
Servo characteristics	P-I, two notch filters
Sampling rate, servo control	10 kHz
Sampling rate, sensor	10 kHz
Sensor	
Sensor type	Metal foil strain gauge sensors (.SR, .SRG), Piezoresistive sensors (.PR, .PRG)
Linearization	5th order polynomials
Sensor bandwidth	5 kHz
Sensor resolution	16 bit
Ext. synchronization	No
Amplifier	
Output voltage	-30 V to +130 V
Peak output power	10 W (<5 ms)
Average output power	5 W (>5 ms)
Peak current	100 mA (<5 ms)
Average current	50 mA (>5 ms)
Current limitation	Short-circuit-proof
Resolution DAC	16 bit
Interfaces and operation	
Communication interfaces	USB, RS-232
Piezo / sensor connector	Sub-D 9-pin
I/O connector	HD-Sub-D 26-pin, 1x analog control input 0 to 10 V, 1x sensor monitor 0 to 10 V, 1x digital input (LVTTL, programmable), 5x digital output (LVTTL, 3x predefined, 2x programmable)
Command set	PI General Command Set (GCS)
User software	PIMikroMove , NanoCapture
Software drivers	LabVIEW drivers, DLLs
Supported functionality	Wave generator, data recorder, auto zero, trigger I/O
Display	Status LED, overflow LED
Miscellaneous	
Operating temperature range	8 to 50 °C (over 40 °C, max. power av. power derated)
Dimensions	160 x 96 x 33 mm
Mass	0.5 kg
Operating voltage	24 VDC
Power consumption	24 W max.

E-761 Digital Piezo Controller

Cost-Efficient PCI Board for Piezo Stages with up to 3 Axes



E-761 Digital Piezo Controller in PCI-Board Format

- **For Piezo Stages with Capacitive Sensors**
- **High-Speed PCI Interface**
- **3 Logical Axes, 4 Piezo Amplifiers**
- **Additional High-Bandwidth Analog Interface**
- **32-Bit Digital Filters**
- **Notch Filter for Higher Bandwidth**
- **24-Bit Ultra-Low-Noise DAC Converters**
- **Auto-Loading of Calibration Data from Stage ID-Chip for Interchangeability of Controller and Mechanics**
- **Coordinate Transformation for Parallel-Kinematics / Parallel-Metrology Systems**
- **Extensive Software Support**

E-761 digital piezo controllers offer advanced control technology in a cost-effective PCI-board format. They were designed to run piezo stages with up to three logical axes. The E-761 incorporates four instrumentation-class, 24-bit digital-analog converters (DAC) behind ultra-low-noise power amplifiers, and is based on a specialized 32-bit digital signal processor (DSP) with proprietary firmware.

Having PCI-board format, the E-761 digital controller can be easily installed in any commercial or industrial PC, allowing for easy integration with other devices such as frame grabbers. The PCI interface with its high bandwidth makes possible a very fast communication between software and controller. This is a definite plus in time-critical applications or when controlling several axes.

Additionally, the E-761.3CT version offers three digital output lines for a variety of triggering tasks.

Improved Trajectory Accuracy Through Parallel Metrology

Digital controllers have a number of advantages over conventional analog piezo controllers. Sensor and actuator axes need not be parallel to each other, or to the orthogonal logical axes used to command the system. The flexible coordinate transformation algorithm permits operation of complex, multi-axis, parallel metrology stages (e. g. 3-axis Z-tip-tilt-stages).

With parallel motion metrology, the controller compensates the undesired off-axis motion of each actuator automatically using the others (active trajectory control). High-end nanopositioning systems with active trajectory control can attain motion accuracies in the sub-nanometer range.

Digital Linearization and Control Algorithms for Highest Accuracy

Linearization algorithms based on higher-order polynomials improve the positioning accuracy to 0.001 % of the travel range.

During fast periodic motion, as typical for scanning applications, the tracking accuracy can be further improved with Dynamic Digital Linearization (DDL, E-710.SCN). This optionally available control algorithm reduces the tracking error by a factor of up to 1000.

The integrated wave generator can save and output periodic motion profiles. In addition to sine and triangle waves, arbitrary, user-defined profiles can be created.

Automatic Configuration

PI digital piezo controllers and nanopositioning stages with ID-chips can be operated in any combination, supported by the controller's AutoCalibration function. Individual stage data and optimized servo-control parameters are stored in the ID-Chips and are read out automatically by the digital controller.

Simple System Integration

All parameters can be set and checked by software. System setup and configuration is done with the included NanoCapture™ and PZTControl™ user-interface software. Interfacing to custom software is facilitated with included LabVIEW drivers and DLLs. All PI controllers use the same command set, a significant advantage during application software development, system upgrade or when operating a variety of different controllers from one application.

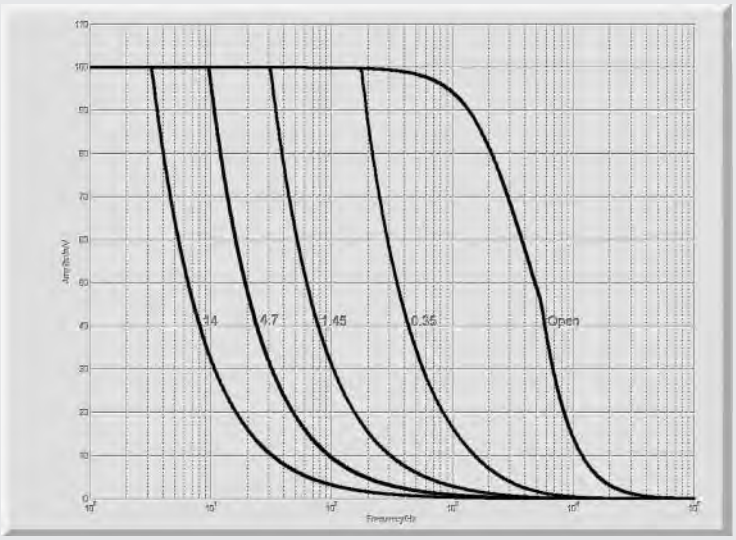
Ordering Information

E-761.3CD
Digital Piezo Nanopositioning Controller, 3 Axes, Sub-D-Special, PCI Board

E-761.00T
Trigger Output Bracket for E-761.3CD

E-761.3CT
Digital Piezo Nanopositioning Controller, 3 Axes, Sub-D-Special, PCI Board, Trigger Output

Ask about custom designs!



E-761: operating limits with various PZT loads (open-loop), capacitance is measured in µF

Technical Data

Model	E-761.3CD	E-761.3CT
Function	Digital piezo controller and power amplifier, PCI board	Digital piezo controller and power amplifier, PCI board, trigger output
Axes	3	3
Processor	32-bit, floating-point DSP	32-bit, floating-point DSP
Sampling rate, servo-control	40 µs / 25 kHz (sensor-oversampling factor 4)	40 µs / 25 kHz (sensor-oversampling factor 4)
Sensor		
Servo characteristics	P-I, two notch filters	P-I, two notch filters
Sensor type	Capacitive	Capacitive
Sensor channels	3	3
Sensor resolution	16-bit	16-bit
Ext. synchronization	Yes	Yes
Amplifier		
Output voltage	-20 to 120 V	-20 to 120 V
Amplifier channels	4	4
Peak output power per channel,	5.3 W	5.3 W
Average output power per channel	1.7 W	1.7 W
Peak current per channel, <20 ms	50 mA	50 mA
Average current per channel, >20 ms	10 mA	10 mA
Current limitation	Short-circuit-proof	Short-circuit-proof
Resolution DAC	24-bit	24-bit
Interfaces and operation		
Interface / communication	PCI connector	PCI connector
Piezo / sensor connector	Sub-D special	Sub-D special
Control Input sockets	LEMO	LEMO
Digital output	-	3 x TTL
Command set	GCS	GCS
User software	NanoCapture™, PZTControl™	NanoCapture™, PZTControl™
Software drivers	LabVIEW drivers, Windows and Linux Libraries (DLL)	LabVIEW drivers, Windows and Linux Libraries (DLL)
Supported functionality	Wave generator	Wave generator, trigger output
Display	Status LED for piezo voltage	Status LED for piezo voltage
Linearization	4th order polynomial	4th order polynomial
Miscellaneous		
Operating temperature range	+5 to +50 °C (derated 10 % over 40 °C)	+5 to +50 °C (derated 10 % over 40 °C)
Overtemp protection	Deactivation at 60 °C	Deactivation at 60 °C
Dimensions	287 x 108 x 25 mm (2 slots)	287 x 108 x 25 mm + 122 x 45x 26 mm (3 slots)
Mass	0.56 kg	0.56 (PCI-board only)
Operating voltage	5 V	5 V
Power consumption	20 W, 4 A max.	20 W, 4 A max.

E-725 Digital Piezo Controller

For 3-Axis High-Speed Precision Positioning Systems

E-725 Digital 3-channel controller with nanopositioning system

Ordering Information

E-725.3CD
Digital Multi-Channel Piezo Controller, 3-Channel, Sub-D Connector for Capacitive Sensors

E-725.3CM
Digital Multi-Channel Piezo Controller, for PicoCube™ and Capacitive Sensors

Ask about custom designs!

- **For Nanopositioning Systems with Capacitive Sensors**
- **3-Channel Version**
- **Powerful Digital Controller: DSP 32-bit Floating Point, 225 MHz; 20 kHz Sampling Rate; 24-bit DAC**
- **Communication via Ethernet, USB, RS-232**
- **4th Order Polynomial Linearization for Mechanics & Electronics**
- **Dynamic Digital Linearization (DDL) Option for Improved Path Accuracy**
- **Auto-Loading of Calibration Data from Stage ID-Chip for Interchangeability of Controller and Mechanics**
- **Additional High-Bandwidth Analog Control Input / Sensor Input**
- **Optional High-Speed Parallel I/O Interface**
- **Flexible Wave Generators**
- **Digital I/O Lines for Task Triggering**
- **Extensive Software Support**

The E-725 digital piezo controller is a compact, high-performance drive electronics for nanopositioning systems with up to three axes. High-power amplifiers permit dynamic scans even for piezo systems with large range or direct drive. State-of-the-art processor technology optimizes the operating parameters for improved linearity and tracking accuracy. High-resolution D/A converters provide for nanopositioning that deserves this name.

With the E-725.3CM, PI for the first time offers a digital controller for the P-363 PicoCube™ (see p. 2-66), a fast precision scanner for atomic force microscopy.

Optional interfaces and analog in- and outputs make it possible to process external sensor or control values.

Digital Linearization and Control Algorithms for Highest Accuracy

Linearization algorithms based on higher-order polynomials improve the positioning accuracy to better than 0.01 % for capacitive sensors, typically 10 times better than achievable with conventional controllers.

More than just a Controller – Trajectory Control and Data Recording

During fast periodic motion, as typical for scanning applications, the tracking accuracy can be further improved with Dynamic Digital Linearization (DDL, E-710.SCN). This optionally available control algorithm reduces the tracking error by a factor of up to 1000.

This control algorithm enables the spatial and temporal tracking during a dynamic scan. The integrated wave generator can output periodic motion profiles. In addition to sine and triangle waves, arbitrary, user-defined motion profiles can be created and stored. The flexibly configurable data recorder enables simultaneous recording and read-out of the corresponding data.

Extensive Software Support

The controllers are delivered with Windows operating software. Comprehensive DLLs and LabVIEW drivers are available for automated control.

Automatic Configuration

PI digital piezo controllers and nanopositioning stages with ID-Chip can be operated in any combination, supported by the AutoCalibration function of the controller. Individual stage data and optimized servo-control parameters are stored in the ID-Chip and are read out automatically by the digital controllers.

Technical Data

Model	E-725.3CD	E-725.3CM	Tolerance
Function	Digital Controller for Multi-Axis Piezo Nanopositioning Systems with Capacitive Sensors	Digital Controller for Multi-Axis Piezo Nanopositioning Systems with Capacitive Sensors	
Axes	3	3	
Processor	DSP 32-bit floating point, 225 MHz	DSP 32-bit floating point, 225 MHz	
Sampling rate, servo-control	20 kHz	20 kHz	
Sampling rate, sensor	20 kHz	20 kHz	
Sensor			
Servo characteristics	P-I, two notch filters	P-I, two notch filters	
Sensor type	Capacitive	Capacitive	
Sensor channels	3	3	
Sensor bandwidth (-3 dB)	5.6 kHz	5.6 kHz	max.
Sensor resolution	18 bit	18 bit	
Ext. synchronization	Yes	Yes	
Amplifier			
Output voltage	-30 to 135 V	-250 to 250 V	±3 V
Amplifier channels	4	4	
Peak output power per channel	25 W	47 W	max.
Average output power per channel*	10 W	10 W	max.
Peak output current per channel	190 mA	190 mA	max.
Average output current per channel*	120 mA	60 mA	max.
Current limitation	Short-circuit proof	Short-circuit proof	
Resolution DAC	24 bit	24 bit	
Interfaces and operation			
Communication interfaces	Ethernet, USB, RS-232	Ethernet, USB, RS-232	
Piezo / sensor connector	Sub-D special connector	Sub-D special connector	
Analog input	1 x Lemo, ±10 V, 18 bit	1 x Lemo, ±10 V, 18 bit	
Digital input / output	MDR20; 2 x IN, 8 x OUT	MDR20; 2 x IN, 8 x OUT	
Command set	PI General Command Set (GCS)	PI General Command Set (GCS)	
User software	NanoCapture™, PIMikroMove™	NanoCapture™, PIMikroMove™	
Software drivers	LabVIEW driver, DLLs	LabVIEW driver, DLLs	
Supported functionality	Wave-Gen, Trigger I/O	Wave-Gen, Trigger I/O	
Display	LEDs for Power, On Target, Error, Cmd	LEDs for Power, On Target, Error, Cmd	
Linearization	4th order polynomial, DDL (Dynamic Digital Linearization)	4th order polynomial, DDL (Dynamic Digital Linearization)	
Separate protective ground connector	Yes	Yes	
Miscellaneous			
Operating temperature range	5 to 50 °C	5 to 50 °C	
Overheat protection	Max. 71 °C, deactivation of the piezo voltage output	Max. 71 °C, deactivation of the piezo voltage output	
Mass	3.5 kg	3.6 kg	
Dimensions	263 x 89 x 302 mm (with handles)	263 x 89 x 302 mm (with handles)	
Power consumption	70 W	70 W	max.
Operating voltage	24 VDC from external power supply (included)	24 VDC from external power supply (included)	

* The total output power of all 4 amplifier channels should not exceed 34.5 W to avoid overcurrent (E-725 is equipped with a 3.15 AM fuse).

New High-Speed 1 kHz Version available

P-545 PInano™ Piezo System for SR-Microscopes

Low-Profile, Low-Cost Nanopositioning Systems for Super-Resolution Microscopy

PI nano™ series nanopositioning stages feature a very low profile of 20 mm (0.8), a large aperture for 3 x 1'' slides and deliver highly accurate motion with sub-nanometer resolution in up to 3 axes. Slide / petri dish holders optional

- **Low Profile for Easy Integration: 20 mm (0.8'')**
- **Up to 200 x 200 x 200 µm Travel Ranges**
- **Large Clear Aperture for 3 x 1'' Slides**
- **Recessed Sample Holders for Maximized Utility Available**
- **Outstanding Lifetime Due to PICMA®Piezo Actuators**
- **Cost-Effective Design due to Piezoresistive Sensors**
- **Compatible w/ Leading Image Acquisition Software Package**
- **Closed-Loop Control for High Repeatability and Accuracy**
- **Millisecond Step Time, Ideal for Super-Resolution Microscopy**
- **24-Bit Controller w/ USB, Ethernet, RS-232 Interface and Analog Control**
- **Available Manual Long-Travel Stage with Motor Upgrade Option**

Long Travel, Low Profile, Optimized for Microscopy

PI nano™ XY and XYZ low-profile piezo scanning stages are optimized for easy integration into high-resolution microscopes. They feature a very low profile of 20 mm (0.8") and a large aperture designed to hold Petri dishes and standard slide holders. The long travel ranges of up to 200 x 200 x 200 µm with nanometer closed-loop resolution are ideal for leading-edge microscopy and imaging applications.

Application Examples

- Super-resolution microscopy
- 3D Imaging
- Laser technology
- Interferometry
- Metrology
- Biotechnology
- Screening
- Micromanipulation

Cost Effective Design, High Performance

PI nano™ series piezo positioning stages are designed to provide high performance at minimum cost. For highly-stable, closed loop operation, piezoresistive sensors are applied directly to the moving structure and precisely measure the displacement of the stage platform. The very high sensitivity of these sensors provides optimum position stability and responsiveness as well as nanometer resolution. A proprietary servo controller significantly improves the motion linearity compared to conventional piezoresistive sensor controllers.

High Reliability and Long Lifetime

The compact P-545 systems are equipped with preloaded PICMA® high-performance piezo actuators which are integrated into a sophisticated, FEA-modeled, flexure guiding system. The PICMA® actuators feature cofired ceramic encapsulation and provide better performance and reliability than conventional piezo actuators. Actuators, guidance and sensors are maintenance-free, not subject to wear and offer extraordinary reliability.

Background: the piezo controller is included and comes with a 24-bit resolution USB port as well as ethernet, RS-232 and analog interface. Foreground: The optional M-545 manual XY stage provides a stable platform for the PI nano™ piezo stages. Custom stage version shown

Ordering Information

P-545.2R7
PInano™ XY Piezo Stage, Slide-Size Aperture, 200 x 200 µm, Piezoresistive Sensors, with USB Controller

P-545.3R7
PInano™ XYZ Piezo Stage, Slide-Size Aperture, 200 x 200 x 200 µm, Piezoresistive Sensors, with USB Controller

Controller included

E-545.3RD
PInano™ Multi-Channel Piezo Controller with High-Speed Digital Interface, 3 Channels, Piezoresistive Sensors, Sub-D Connectors

Accessories

M-545.2MO
XY Microscope Stage, 25 x 25 mm, Micrometer-Driven, High Stability, Compatible with PI® Piezo Stages, for Olympus Microscopes

M-545.2MN
XY Microscope Stage, 25 x 25 mm, Micrometer-Driven, High Stability, Compatible with PI® Piezo Stages, for Nikon Microscopes

M-545.2ML
XY Microscope Stage, 25 x 25 mm, Micrometer-Driven, High Stability, Compatible with PI® Piezo Stages, for Leica Microscopes

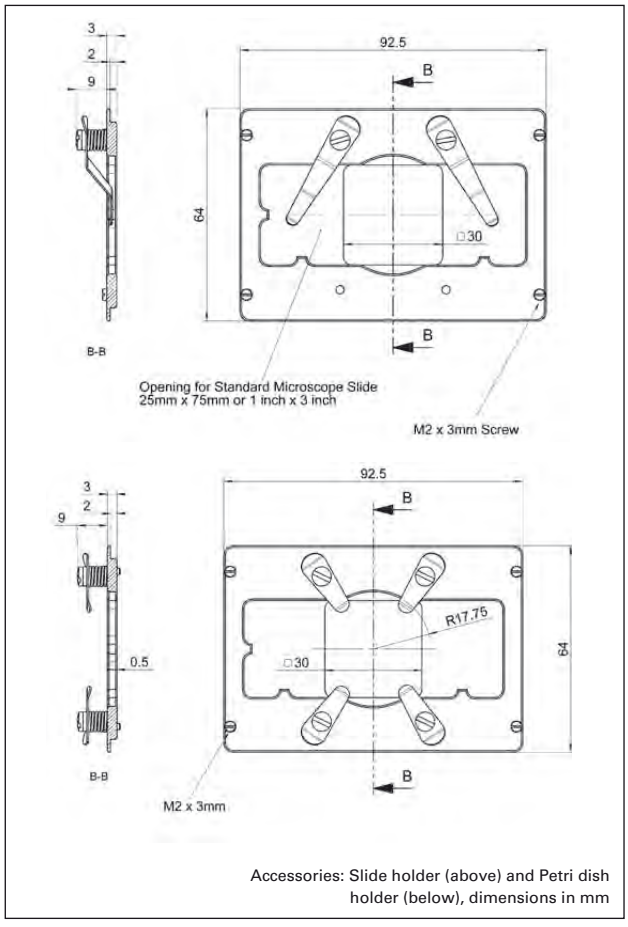
M-545.2MZ
XY Microscope Stage, 25 x 25 mm, Micrometer-Driven, High Stability, Compatible with PI® Piezo Stages, for Zeiss Microscope

P-545.PD3
35mm Petri Dish Holder for P-545 PInano™ Piezo Stages

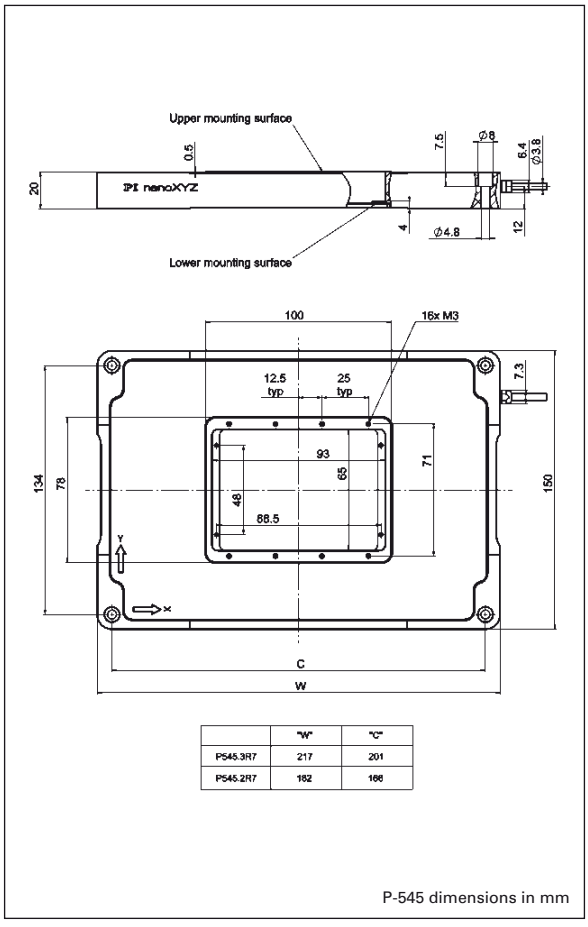
P-545.SH3
Microscope Slide Holder for PInano™ Piezo Stages

P-545.PP3
Plain Plate for Accessories for PInano™ Piezo Stages

Additional accessories on request.



Accessories: Slide holder (above) and Petri dish holder (below), dimensions in mm



P-545 dimensions in mm

Technical Data

Model	P-545.2R7	P-545.3R7	Unit	Tolerance
Active axes	X, Y	X, Y, Z		
Motion and positioning				
Integrated sensor	piezoresistive	piezoresistive		
Closed-loop travel	200 x 200	200 x 200 x 200	µm	
Closed-loop resolution*	1	1	nm	typ.
Linearity	±0.1	±0.1	%	typ.
Repeatability	< 5	< 5	nm	typ.
Mechanical properties				
Push/pull force capacity	100 / 30	100 / 30	N	max.
Load	50	50	N	max.
Drive properties				
Ceramic type	PICMA® P-885	PICMA® P-885		
Electrical capacitance	6	6 (X, Y), 12 (Z)	µF	±20%
Miscellaneous				
Operating temperature range	-20 to 80	-20 to 80	°C	
Material	Aluminum	Aluminum		
Mass	1	1.2	kg	±5%
Cable length	1.5	1.5	m	±10 mm
Sensor / voltage connection	Sub-D, 25 pin	Sub-D, 25 pin		
Piezo controller (included in delivery)	E-545	E-545		

* Resolution of PI Piezo Nanopositioners is not limited by friction or stiction. Value given is noise equivalent motion measured with interferometer.

M-545 High Stability Microscope Stage

Long-Range Motion for Sample Positioning

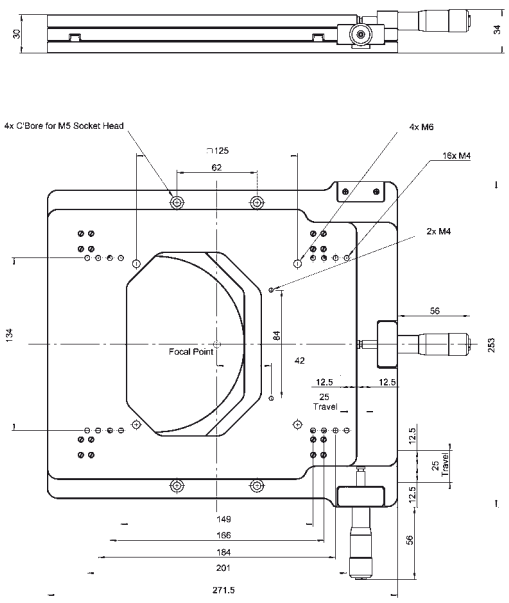
The M-545 stage was designed to provide a stable basis for piezo stages, especially when the highest step-and-settle performance is required

The M-545, 25 x 25 mm microscope stage, is designed to provide a stable platform for piezo scanning stages of the P-545 PInano™ series. These high-speed, high-resolution XY / XYZ piezo stages allow nanometer-precision adjustment of the specimen holder in up to three dimensions over 200 µm. The M-545 is also compatible with the following capacitive-feedback type piezo stages: P-733, P-5x7, P-5x8, P-54x and P-56x (s. p. 2-72).
The basic M-545 model is equipped with manual micrometers.

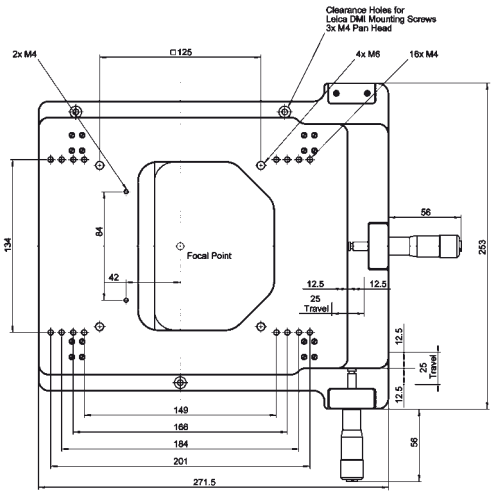
Motorizing for Automated Tasks
The M-545 XY-stage can be supplemented with motorized actuators M-229 (s. p. 1-44). The product number M-545.USC comprises the complete package of two stepper linear actuators with controller and joystick. M-545.USG includes two stepper linear actuators with mounting

- **Stable Platform for P-545 PInano™ Piezo Nanopositioning Systems**
- **Low Profile for Easy Integration: 30 mm**
- **25 mm x 25 mm Travel Range**
- **Micrometer Screws, Motor Upgrade Available**
- **For Nikon, Zeiss, Leica and Olympus Mikroscopes**

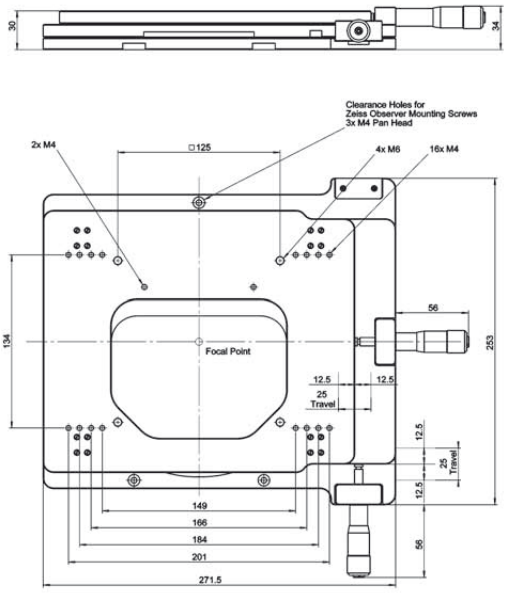
M-545 version with ultrasonic linear motors provides high speed and stability



M-545.2MO, M-545.2MN dimensions in mm.
Mounting adapters for Olympus and Nikon microscopes respectively included in delivery



M-545.2ML dimensions in mm



M-545.2MZ dimensions in mm

Technical Data

Model	M-545.2M	Unit	Tolerance
Active axes	XY		
Motion and positioning			
Displacement	25 x 25	mm	
Min. incremental motion	1	µm	typ.
Min. incremental motion with M-229 stepper linear actuators	1	µm	typ.
Velocity with M-229 stepper linear actuators	1.5	mm/s	max.
Mechanical properties			
Max. load	50	N	
Preload	10	N	
Miscellaneous			
Material	Aluminum, stainless steel		
Mass	4	kg	±5%

Find further specifications on M-229 stepper linear actuators in the datasheet (s. p. 1-44)

M-545 manual XY microscopy stage with 25 x 25 mm travel shown with optional PInano™ piezo nanopositioner (200 µm motion in X, Y und Z) on top.

Ordering Information

M-545.2MO
XY Microscope Stage, 25 x 25 mm, Micrometer Drive, High Stability, Compatible with PI Piezo Stages, for Olympus Microscopes

M-545.2MN
XY Microscope Stage, 25 x 25 mm, Micrometer Drive, High Stability, Compatible with PI Piezo Stages, for Nikon Microscopes

M-545.2ML
XY Microscope Stage, 25 x 25 mm, Micrometer Drive, High Stability, Compatible with PI Piezo Stages, for Leica Microscopes

M-545.2MZ
XY Microscope Stage, 25 x 25 mm, Micrometer Drive, High Stability, Compatible with PI Piezo Stages, for Zeiss Microscope

Versions for other microscopes on request.

Accessories

M-545.USC
Factory Installed Stepper-Mike Upgrade for M-545 XY Microscope Stages: Includes Stepper-Mikes, Joystick and Controller

M-545.USG
Factory Installed Stepper-Mike Upgrade for M-545 XY Microscope Stages: Includes Stepper-Mikes, Joystick

M-545.SHP
Adapter Plate for Sample Holders for M-545 XY Microscope Stages

Accommodates the following PI nanopositioning stage series:
P-517/518/527/528, P-541/542, P-560 PIMars and P-545 PInano™

Adapter available for P-733 nanopositioners:

P-733.AP1
Adapter Plate for Mounting of P-733 Piezo Stages on M-545 XY Microscope Stage

Additional accessories on request.

M-686 PILine® High Stability 25x25 mm XY Piezo Motor Stage

Ideal Base for Piezo Scanning Stages

The M-686.D64 open-frame stage with closed-loop piezo motors provides 25 x 25 mm travel range

- **Integrated Closed-Loop Piezomotor Drives Provide High Speed to 100 mm/s**
- **Travel Ranges 25 x 25 mm**
- **Integrated Linear Encoders with 0.1 µm Resolution**
- **Compact Design: 32 mm Profile Height, 170 x 170 mm Footprint**
- **Clear Aperture 78 x 78 mm, 66 x 66 mm in Extreme Position**
- **Self-Locking at Rest**
- **Compatible with PI Piezo Nanopositioning / Scanning Stages**

M-686 open-frame piezomotor stages are mainly designed for automated positioning applications in microscopy . The optimized form factor with a low profile height of only 32 mm and the standardized mounting pattern allows the combination with many PI standard nanopositioning systems.

Application Examples

- Biotechnology
- Microscopy
- Scanning microscopy
- Confocal microscopy
- Semiconductor testing
- Handling

Space Saving Piezomotors

Compared to conventional motorized translation stages, the M-686 provides a lower profile and smaller footprint. The compact PILine® piezoelectric linear motors and high-resolution linear encoders make both, the lead screw duct and the flanged, bulky stepper motor employed in traditional stages obsolete. In addition, the piezomotors are self-locking at rest and hold the stage in a stable position without heating up.

Compatibility to PI Nanopositioning and Scanning Stages

A number of standard PI piezo flexure stages (150 x 150 mm footprint) can be mounted directly on the M-686 open-frame stage. Depending on the application, these highly specialized, ultra-precise nanopositioning systems are available as fast XY scanners (for fluorescence microscopy), as vertical Z positioners (3D imaging), or with up to 6 degrees of freedom.

Limit and Reference Switches

For the protection of your equipment, non-contact Hall-effect limit and reference switches are installed. The direction-sensing reference switch supports advanced automation applications with high precision.

Advantages of PILine® Micropositioning Systems

The ultrasonic piezoceramic drives used in Plline® micropositioners have a number of advantages over classical drives:

- Higher Accelerations, up to 5 g
- Speeds up to 500 mm/s
- Small Form Factor
- Self-Locking When Powered Down
- No Shafts, Gears or Other Rotating Parts
- Non-Magnetic and Vacuum-Compatible Drive Principle

Ordering Information

M-686.D64
XY Open-Frame Stage with Closed-Loop PILine® Piezomotor Drives, 25 x 25 mm, 7 N, 0.1 µm Linear Encoder

Ask about custom designs!

Notes

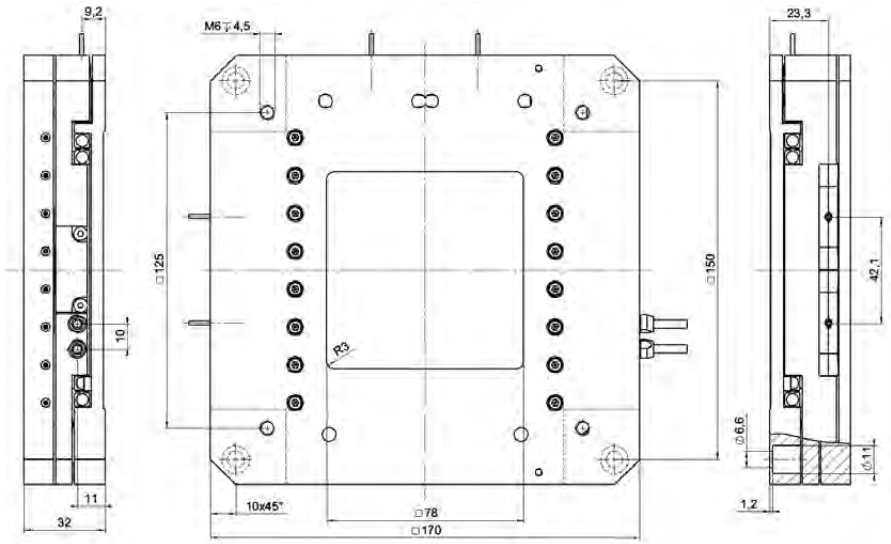
Nanopositioning stages that fit directly on the M-686:

P-561 to P-563
PIMars™ XYZ Nanopositioning systems with up to 300 µm travel

P-541.2 to P-542.2
Low-profile microscopy XY scanners

P-541.Z
Low-profile Z/tip/tilt piezo nanopositioning stages for microscopy

The two-channel C-867.260 controller operates XY scanning stages, here: a customized M-686 stage for microscopy



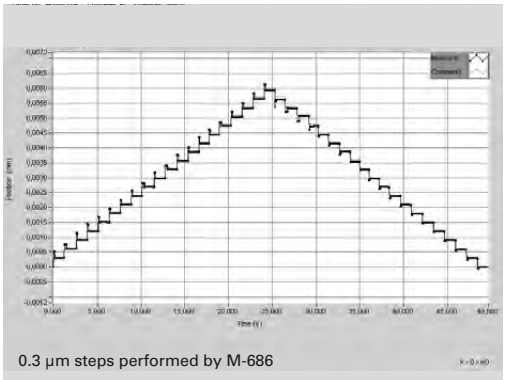
M-686.D64, dimensions in mm. The minimum aperture is 66 x 66 mm with both axes at the maximum position

Technical Data

Model	M-686.D64
Active axes	XY
Motion and positioning	
Travel range	25 x 25 mm
Integrated sensor	Linear encoder
Sensor resolution	0.1 µm
Design resolution	0.1 µm
Min. incremental motion	0.3 µm
Bidirectional repeatability	0.3 µm
Pitch / yaw	±50 µrad
Max. velocity	100 mm/s
Mechanical properties	
Load Capacity*	50 N
Max. push/pull force	7 N
Max. lateral force	4 N
Drive properties	
Motor type	2 x PILine® P-664 per axis
Operating voltage	190 V (Peak-Peak)** 67 V (RMS)**
Electrical power	10 W / axis***
Miscellaneous	
Operating temperature range	-20 to +50 °C
Material	Aluminium (black anodized)
Mass	1.2 kg
Cable length	1.5 m
Connector	2 x MDR connector, 14-pin
Recommended controller/driver	2 x C-867.D64 single-axis controller / driver 2 x C-185.D64 single-axis drive electronics for external servo-controllers (p. 4-116, p. 1-36)

*10 N for max. velocity
**The operating voltage or the piezomotor is supplied by the drive electronics which requires 12 VDC
***For drive electronics

M-686 open-frame stage with P-541.2DD piezo scanner on top, providing a resolution of 0.1 nm and a scanning range of 30 x 30 µm. The system height of the combination with the P-541 XY (or Z) piezo scanner is only 48 mm

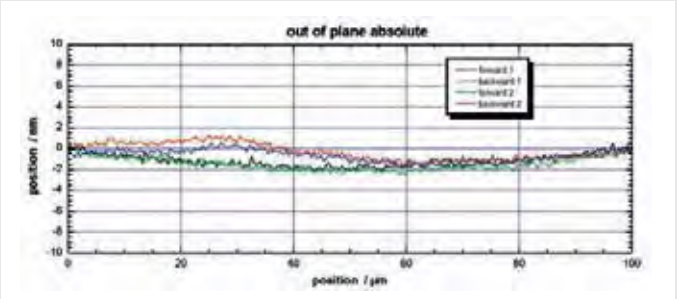


0.3 µm steps performed by M-686

P-734 Low Bow XY Piezo Stage

High-Dynamics System with Minimum Runout & Clear Aperture

P-734 low-bow flexure nanopositioning stage with ultra-precise trajectory control



Typical flatness of P-734 motion is in the low nanometer range

P-734 high-dynamics, XY piezo nanopositioning stages feature linear travel ranges to 100 x 100 µm with sub-nanometer resolution and maximum flatness of motion.

Flatness in the Low Nanometer Range

P-734 open-frame XY nanopositioning and scanning stages are ideal for nanometrology tasks that require extreme flatness of scanning. These stages feature an ultra-precise, flexure guiding system which confines motion to the XY plane and reduces runout in Z to a few nanometers or less. This unsurpassed trajectory precision is fundamental for highest-precision surface metrology applications. These stages provide a positioning and scanning range of 100 x 100 µm with accuracy and resolution in the nanometer and sub-nanometer range.

Application Examples

- Scanning microscopy
- Metrology / interferometry
- Semiconductor testing
- Mask/wafer positioning
- Image processing / stablilization
- Biotechnology
- Micromanipulation
- Nanopositioning

Excellent Guiding Accuracy

Flexures optimized with Finite Element Analysis (FEA) are used to guide the stage. FEA techniques are used to give the design the highest possible stiffness in, and perpendicular to, the direction of motion, and to minimize linear and angular runout. Flexures allow extremely high-precision motion, no matter how minute, as they are completely free of play and friction.

Higher Precision in Periodic Motion

The highest dynamic accuracy in scanning applications is made possible by the DDL algorithm, which is available in PI's modern digital controllers. DDL eliminates tracking errors, improving dynamic linearity and usable bandwidth by up to three orders of magnitude!

Direct Position Measurement with Sub-Nanometer Accuracy

PI's proprietary capacitive sensors measure position directly and without physical contact. They are free of friction and hysteresis, a fact which, in combination with the positioning resolution of well under 1 nm, makes it possible to achieve very high levels of linearity. A further advantage of direct metrology with capacitive sensors is the high phase fidelity and the high bandwidth of up to 10 kHz.

Parallel Kinematics and Metrology with Capacitive Sensors for High Trajectory Fidelity

In a parallel kinematics multi-axis system, all actuators act directly on one moving platform. This means that all axes move the same minimized mass and can be designed with identical dynamic properties. Systems with parallel kinematics and metrology have additional advantages over serially stacked or nested systems, including more-compact construction and no cumulative error from the different axes. Parallel kinematics systems can be operated with up to six degrees of freedom with low inertia and excellent dynamic performance. Multi-axis nanopositioning systems equipped with both parallel kinematics and parallel, direct metrology are able to measure platform position in all degrees of freedom against one common fixed reference. In such systems, undesirable motion from one actuator in the direction of another (cross talk) is detected immediately and actively compensated by the servo-loops. This Active Trajectory Control Concept can keep deviation from a trajectory to under a few nanometers, even in dynamic operation.

Ordering Information

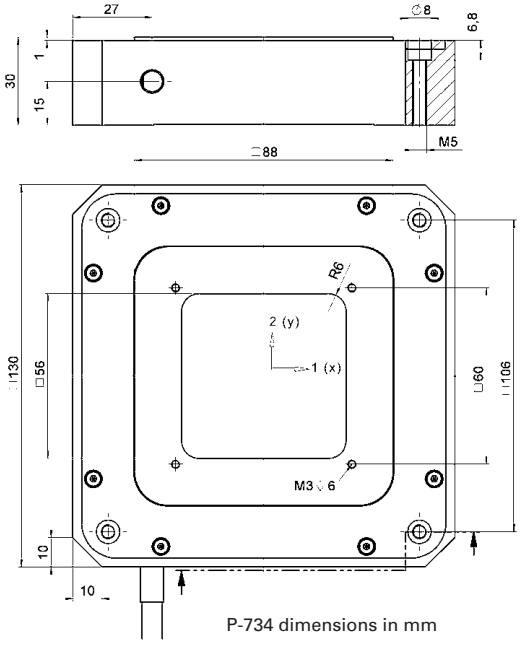
P-734.2CD
High-Precision XY Nanopositioning System with Minimum Runout, 100 x 100 µm, Capacitive Sensors, Parallel Metrology, Sub-D Connector

P-734.2CL
High-Precision XY Nanopositioning System with Minimum Runout, 100 x 100 µm, Capacitive Sensors, Parallel Metrology, LEMO Connector

- **Ultra-Precision Trajectory Control, Ideal for Surface Analysis and Scanning Microscopy**
- **Parallel-Kinematics / Metrology for Enhanced Responsiveness / Multi-Axis Precision**
- **Travel Range 100 x 100 µm, Clear Aperture 56 x 56 mm**
- **Capacitive Sensors for Resolution <0,4 nm**
- **Outstanding Lifetime Due to PICMA® Piezo Actuators**

Ceramic Insulated Piezo Actuators Provide Long Lifetime

Highest possible reliability is assured by the use of award-winning PICMA® multilayer piezo actuators. PICMA® actuators are the only actuators on the market with ceramic-only insulation, which makes them resistant to ambient humidity and leakage-current failures. They are thus far superior to conventional actuators in reliability and lifetime.



P-734 dimensions in mm

E-725 Digital 3-channel controller with nanopositioning system

Technical Data

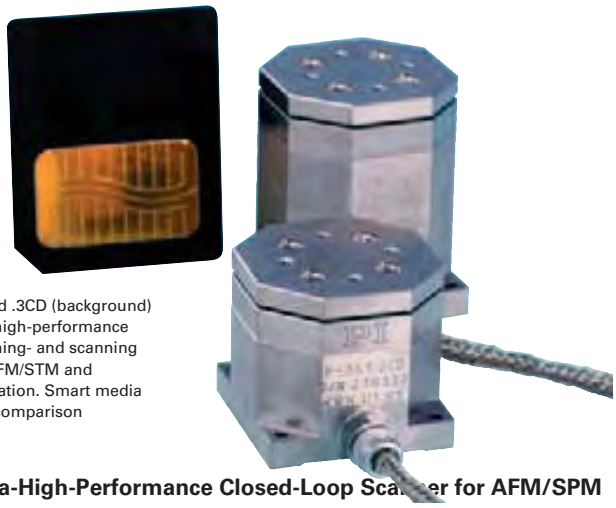
Models	P-734.2CL	P-734.2CD	Units	Tolerance
Active axes	X, Y	X, Y		
Motion and positioning				
Integrated sensor	Capacitive	Capacitive		
Open-loop travel, -20 to +120 V	110 x 110	110 x 110	µm	min. (+20 %/-0 %)
Closed-loop travel	100 x 100	100 x 100	µm	
Open-loop resolution	0.2	0.2	nm	typ.
Closed-loop resolution	0.3	0.3	nm	typ.
Linearity	0.03	0.03	%	typ.
Repeatability	<2.5	<2.5	nm	typ.
Pitch	<3	<3	µrad	typ.
Yaw	<10	<10	µrad	typ.
Flatness	typ. <5, max. <10	typ. <5, max. <10	nm	typ.
Mechanical properties				
Stiffness	3	3	N/µm	±20 %
Unloaded resonant frequency	500	500	Hz	±20 %
Resonant frequency @ 200 g	350	350	Hz	±20 %
Resonant frequency @ 500 g	250	250	Hz	±20 %
Push/pull force capacity in motion direction	300 / 100	300 / 100	N	Max.
Load capacity	20	20	N	Max.
Drive properties				
Ceramic type	PICMA® P-885	PICMA® P-885		
Electrical Capacitance	6.2	6.2	µF	±20%
Dynamic operating current coefficient	7.8	7.8	µA/(Hz • µm)	±20%
Miscellaneous				
Operating temperature range	-20 to 80	-20 to 80	°C	
Material	Aluminum	Aluminum		
Mass (with cables)	1.04	1.04	kg	±5 %
Cable length	1.5	1.5	m	±10 mm
Sensor connection	2x LEMO	Sub-D Special		
Voltage connection	4x LEMO	Sub-D Special		

Dynamic Operating Current Coefficient in µA per Hz and µm. Example: Sinusoidal scan of 10 µm at 10 Hz requires approximately 7.8 mA drive current.

Recommended controller / amplifier
P-734.2CL (p. 2-64): E-500 modular piezo controller system (p. 2-142) with amplifier module E-503 (three channels) (p. 2-146) or E-505 (1 per axis, high performance) (p. 2-147) and E-509 controller (p. 2-152)
P-734.2CD (p. 2-64): Multi-channel digital controllers: E-710/E-725 bench-top (p. 2-128, p. 2-126), E-712 modular (p. 2-140), E-761 PCI board (p. 2-130)

P-363 PicoCube™ XY(Z) Piezo Scanner

High-Dynamics Nanoscanner for Scanning Probe Microscopy



P-363.2CD and .3CD (background) PicoCube™, high-performance piezo positioning- and scanning systems or AFM/STM and nanomanipulation. Smart media card for size comparison

- **Ultra-High-Performance Closed-Loop Scanner for AFM/SPM**
- **Compact Manipulation Tool for Bio/Nanotechnology**
- **Resonant Frequency 9.8 kHz**
- **Capacitive Sensors for Highest Accuracy**
- **Parallel-Motion Metrology for Automated Compensation of Guiding Errors**
- **50 Picometer Resolution**
- **5 x 5 x 5 µm Travel Range**
- **Vacuum-Compatible Versions**

The P-363 PicoCube™ XY/XYZ is an ultra-high-performance closed-loop piezo scanning system. Designed for AFM, SPM and nanomanipulation applications, it combines an ultra-low inertia, high-speed XY/XYZ piezo scanner with non-contact, direct-measuring, parallel-metrology capacitive feedback capable of 50 picometers resolution. On top of being extremely precise, the PicoCube™ system is also very small and rugged. Measuring only 30 x 30 x 40 mm (with removable top plate, 30 x 30 x 28 mm for XY version), it is easy to integrate in any scanning apparatus.

Application Examples

- Scanning microscopy (SPM)
- Biotechnology
- Micromanipulation
- Nanopositioning
- Nano-imprinting
- Nanometrology
- Nanolithography

SPM, AFM, STM, Nanolithography, Nanoimprinting, Nanometrology

The PicoCube™ was specifically developed to overcome the limitations of the open-loop scanners currently available for SPM, AFM and STM. In addition to these applications, the PicoCube™ is also the ideal scanning and manipulation tool for nanoimprinting, nanolithography, ultra-high-resolution, near-field, scanning optical microscopy and nanosurface-metrology applications.

Higher Precision Through Parallel-Motion Metrology w/ Capacitive Sensors

The PicoCube™ is based on a proprietary, ultra-fast, piezo-driven scanner design equipped with direct-measuring, capacitive position sensors (parallel metrology). Unlike conventional sensors, they measure the actual distance between the fixed frame and the moving part of the stage. This results in higher-motion linearity, long-term stability, phase fidelity, and—because external disturbances are seen by the sensor immediately—a stiffer, faster-responding servo-loop.

Multi-axis nanopositioning systems equipped with parallel direct metrology are able to measure the platform position in all degrees of freedom against one fixed reference. In such systems, undesirable motion from one actuator in the direction of another (cross-talk) is detected immediately and act ively compensated by the servo-loops. This Active Trajectory Control Concept can keep deviation from a trajectory to under a few nanometers, even in dynamic operation.

Ordering Information

P-363.3CD
PicoCube™ High-Precision XYZ Nanopositioning System, 5 x 5 x 5 µm, Parallel Metrology, Capacitive Sensors, Sub-D Connector

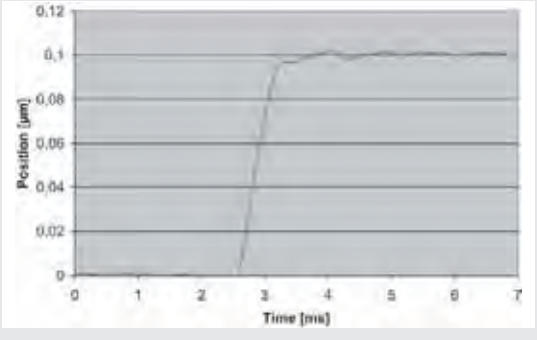
P-363.3UD
PicoCube™ High-Precision XYZ Nanopositioning System, 5 x 5 x 5 µm, Parallel Metrology, Capacitive Sensors, Sub-D Connector, Vacuum Compatible to 10^{-9} hPa

P-363.2CD
PicoCube™ High-Precision XY Nanopositioning System, 5 x 5 µm, Parallel Metrology, Capacitive Sensors, Sub-D Connector

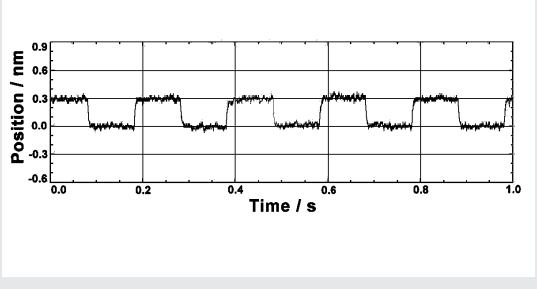
P-363.2UD
PicoCube™ High-Precision XY Nanopositioning System, 5 x 5 µm, Parallel Metrology, Capacitive Sensors, Sub-D Connector, Vacuum Compatible to 10^{-9} hPa

P-363.3CL
PicoCube™ High-Precision XYZ Nanopositioning System, 5 x 5 x 5 µm, Parallel Metrology, Capacitive Sensors, LEMO Connector

P-363.2CL
PicoCube™ High-Precision XY Nanopositioning System, 5 x 5 µm, Parallel Metrology, Capacitive Sensors, LEMO Connector



The P-363 settles to within 1 nm in 1 ms (100 nm step, X and Y motion; faster response in Z)



300 picometer steps (0.3 nm) performed with the P-363, measured with an external high-resolution, capacitive measurement system

Paper on Molecular Stretching Application

Nanometer Accuracy in 1 Millisecond with 30-Picometer Resolution

PicoCube™ systems provide resolution of 30 picometers and below. The ultra-fast XY/XYZ piezo drives offer resonant frequencies of 9.8 kHz in Z and >3 kHz in X and Y! The high resonant frequency and high-bandwidth capacitive feed back allow step and settle to 1% accuracy in as little as one millisecond.

Rugged Design

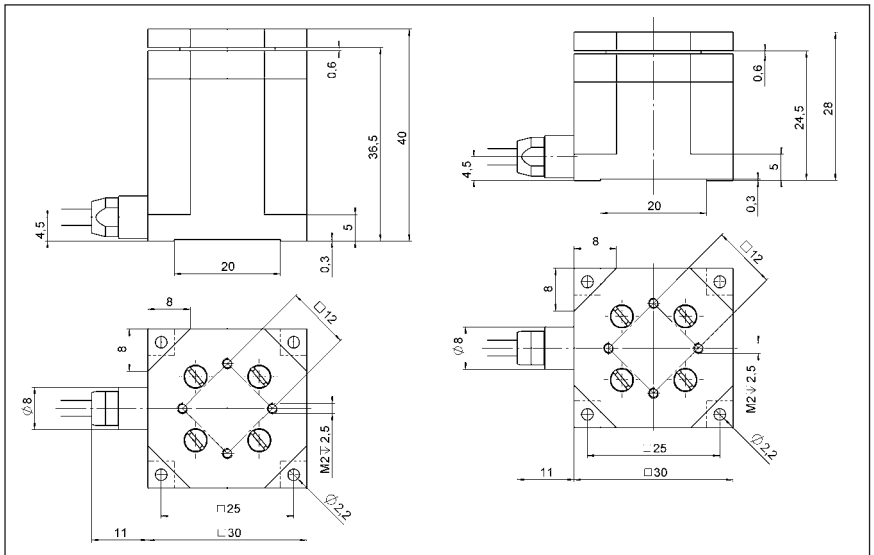
In spite of its ability to move and position on an atomic scale, the PicoCube™ boasts a rugged design for real-world applications. For extra-high stability and reduced mass, the body is precision machined from heat-treated and stress-relieved titanium. The sophisticated frictionless design also ensures that the (moving) top plate protects the internal actuator/sensor unit from contamination.

Controller

For dynamic scanning opera - tion the E-725.3CM high-power digital controller offers advanced linearization algorithms for sub-nanometer precision (see p. 2-126).

Alternatively the analog E-536 PicoCube™ controller (see p. 2-134) comes in different versions optimized for resolution or power . An optional E-517 24-bit interface module is also available (see p. 2-156).

E-536 controller with P-363 PicoCube® pico-positioning system



P-363.3Cx dimensions in mm. Removable top plate

P-363.2Cx dimensions in mm. Removable top plate

Technical Data

Model	P-363.3CD	P-363.2CD	Units
Active axes	X, Y, Z	X, Y	
Motion and positioning			
Integrated sensor	Capacitive	Capacitive	
Open-loop travel X, Y, -250 to +250 V	±3	±3	µm
Open-loop travel, -250 to +250 V	±2.7	–	µm
Closed-loop travel X, Y	±2.5	±2.5	µm
Closed-loop travel	±2.5	–	µm
Open-loop resolution	0.03*	0.03*	nm
Closed-loop resolution	0.1	0.1nm	
Linearity	0.05	0.05	%
Repeatability	1**	1**	nm
Pitch / yaw in X, Y	0.5	0.5	µrad
Runout X, Y (Z motion)	0.2	–	µrad
Straightness in X, Y	3	3	nm
Flatness in X, Y	<10	<10	nm
Crosstalk X, Y (Z motion)	5	–	nm
Mechanical properties			
Unloaded resonant frequency in X, Y	3.1	4.2	kHz
Unloaded resonant frequency (Z)	9.8	–	kHz
Resonant frequency in X, Y	1.5 (20 g)	2.1 (20 g)	kHz
Load capacity	10	10	N
Ceramic type	PICA™, PICA™ Shear	PICA™ Shear	
Miscellaneous			
Operating temperature range	-20 to 80	-20 to 80	°C
Material	Titanium	Titanium	
Dimensions	30 x 30 x 40	30 x 30 x 28	mm
Mass	225	190	g
Cable length	1.5	1.5	m
Sensor / voltage connection***	Sub-D connector PicoCube™	Sub-D connector PicoCube™	
Recommended controller	E-536 PicoCube™ Controller	E-536 PicoCube™ Controller	

Resolution of PI Piezo Nanopositioners is not limited by friction or stiction. V alue given is noise equivalent motion with E-536 controller (p. 2-134)

*With E-536.3xH Controller

**for 10% travel in Z; 50 nm for 100 % travel in Z

***P-363.xCL versions with LEMO connectors

System properties

System configuration	P-363.3CD (Z-axis) with 20 g load and E-536 servo controller
Settling time	(10 % step width) 1 ms

P-733 High Speed Piezo-Nanopositioning Stage

High-Precision XY(Z) Scanner Family with Aperture

P -733.3 DD (left) and P -733.2 DD, high-speed, direct drive XY(Z) scanning stages are the fastest scanning stages with large aperture currently available (2.2 kHz resonant frequency!). Both units feature a footprint of only 100 x 100 mm. CD for size comparison.

- **Travel Ranges to 100 x 100 µm in X,Y & to 10 µm in Z**
- **Resolution to 0.1 nm with Capacitive Sensors**
- **High-Speed Versions with Direct Drive**
- **Vacuum and Non-Magnetic Versions**
- **Parallel Kinematics for Better Multi-Axis Accuracy and Dynamics**
- **Parallel Metrology for Active Trajectory Control**
- **Frictionless, High-Precision Flexure Guiding System**
- **Clear Aperture 50 x 50 mm for Transmitted-Light Applications**

P-733 XY and XYZ piezo driven stages are fast and highly accurate nanopositioning and scanning systems. They provide a positioning and scanning range of 100 x 100 (x10) µm together with sub-nanometer resolution and are equipped with parallel-metrology capacitive position feedback for superior multi-axis linearity and repeatability. The guiding accuracy minimizes runout to under 10 nm over the whole travel range. In addition, the high-speed Z-axis of the P-733.3CD can actively compensate any out-of-plane Z-axis deviation during XY motion.

Application Examples

- Image processing / stablilization
- Scanning microscopy
- Surface inspection
- Metrology / interferometry
- Biotechnology
- Semiconductor testing
- Mask / wafer positioning
- Micromanipulation
- Nanopositioning with high flatness & straightness

Fastest Multi-Axis Systems / Direct Drive, Low Profile and Large Apertures

P-733.2DD / .3DD multi-axis piezo nanopositioning systems are the fastest ultra-high-precision, open-frame stages for scanning microscopy. They provide a positioning and scanning range of 30 x 30 (x10) µm. P-733 nanopositioning and scanning stages feature very low profiles, as low as 20 mm (0.8 inch). The novel, high-stiffness direct drive gives the systems resonant frequencies as high as 2.2 kHz (4 x that of other comparable systems), enabling millisecond scanning rates with sub-nanometer resolution.

Parallel-Kinematics / Metrology for Enhanced Responsiveness

In a parallel kinematics multi-axis system, all actuators act directly on one moving platform. This means that all axes move the same minimized mass and can be designed with identical dynamic properties. Multi-axis nano positioning systems equipped with both parallel kinematics and parallel, direct metrology are able to measure platform position in all degrees of freedom against one common fixed reference. In such systems, undesirable motion from one actuator in the direction of another (cross talk) is detected immediately and actively compensated by the servo-loops.

Capacitive Sensors for Subnanometer Resolution

PI's proprietary capacitive sensors measure position directly and without physical contact. They are free of friction and hysteresis, a fact which, in combination with the positioning resolution of well under 1 nm, makes it possible to achieve very high levels of linearity. A further advantage of direct metrology with capacitive sensors is the high phase fidelity and the high bandwidth of up to 10 kHz. The closed-loop resolution is 0.3 nm for the X and Y axes and 0.2 nm for the optional Z-axis. The direct drive versions are rated to 0.1 nm resolution for every axis.

Large Variety of Models for a Broad Range of Applications

For Z-axis scanning appli cations, the P-733.ZCD (see p. 2-42) version is available with a travel range of 100 µm. For ultra-high-vacuum appli cations down to 10^{-9} hPa, nanopositioning systems as well as comprehensive accessories, such as suitable feedthroughs, are available.

Ordering Information

P-733.2DD
High-Dynamics High-Precision XY Nanopositioning System, 30 x 30 µm, Direct Drive, Capacitive Sensors, Parallel Metrology, Sub-D Connector

P-733.3DD
High-Dynamics Precision XYZ Nanopositioning System, 30 x 30 x 10 µm, Direct Drive, Capacitive Sensors, Parallel Metrology, Sub-D Connector

P-733.2CD* / P-733.2CL*
High-Precision XY Nanopositioning System, 100 x 100 µm, Capacitive Sensors, Parallel Metrology

P-733.3CD* / P-733.3CL*
Precision XYZ Nanopositioning System, 100 x 100 x 10 µm, Capacitive Sensors, Parallel Metrology

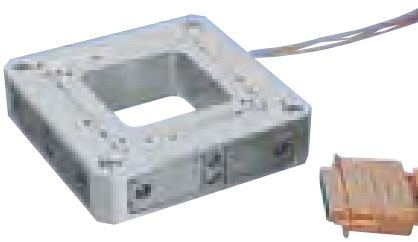
P-733.2VL* / P-733.2VD*
High-Precision XY Nanopositioning System, 100 x 100 µm, Capacitive Sensors, Parallel Metrology, Vacuum Compatible to 10-6 hPa

P-733.2UD
High-Precision XY Nanopositioning System, 100 x 100 µm, Capacitive Sensors, parallel metrology, Sub-D Connector, Vacuum Compatible to 10-9 hPa

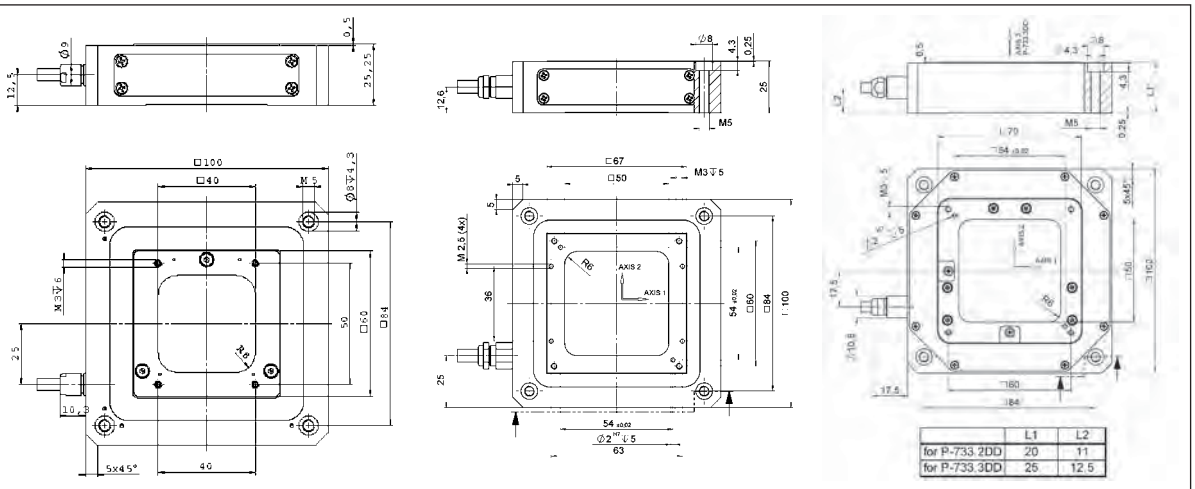
*.xxD with Sub-D Connector

*.xxL with LEMO Connector

Ask about custom designs



P-733.2UD non-magnetic XY scanning stage for UHV to 10^{-9} hPa



P-733.2 dimensions in mm

P-733.3 dimensions in mm

P-733.xDD dimensions in mm

Technical Data

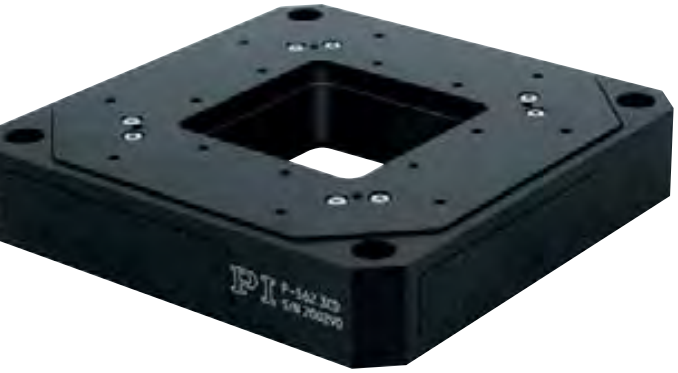
Model	P-733.2CD P-733.2CL	P-733.3CD P-733.3CL	P-733.2DD	P-733.3DD	Units	Tolerance
Active axes	X, Y	X, Y, Z	X, Y	X, Y, Z		
Motion and positioning						
Integrated sensor	Capacitive	Capacitive	Capacitive	Capacitive		
Open-loop travel, -20 to +120 V	115 x 115	115 x 115 x 12	33 x 33	33 x 33 x 14	µm	min. (+20 %/-0 %)
Closed-loop travel	100 x 100	100 x 100 x 10	30 x 30	30 x 30 x 10	µm	
Open-loop resolution	0.2	0.2 (0.1 in Z)	0.1	0.1	nm	typ.
Closed-loop resolution	0.3	0.3 (0.2 in Z)	0.1	0.1	nm	typ.
Linearity (X, Y)	0.03	0.03	0.03*	0.03*	%	typ.
Linearity (Z)	–	0.03	–	0.03*	%	typ.
Repeatability (X, Y)	<2	<2	<2	<2	nm	typ.
Repeatability (Z)	–	<1	–	<1	nm	typ.
Pitch (X,Y)	<±3	<±3	<±5	<±5	µrad	typ.
Yaw (X, Y)	<±10	<±10	<±10	<±10	µrad	typ.
Runout θZ (motion in Z)		<±5		<±5	µrad	typ.
Mechanical properties						
Stiffness	1.5	1.4 (9 in Z)	20	4 (10 in Z)	N/µm	±20 %
Unloaded resonant frequency	500	460 (1400 in Z)	2230	1200 (1100 in Z)	Hz	±20 %
Resonant frequency @ 120 g	370	340 (1060 in Z)	-	-	Hz	±20 %
Resonant frequency @ 200 g	340	295 (650 in Z)	1550	530 (635 in Z)	Hz	±20 %
Push/pull force capacity in motion direction	50/20	50/20	50/20	50/20	N	Max.
Drive properties						
Ceramic type	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885		
Electrical capacitance	6	6 (2.4 in Z)	6.2	6.2 (3.3 in Z)	µF	±20 %
Dynamic operating current coefficient	7.5	7.5 (30 in Z)	25	25 (41 in Z)	µA	(Hz • µm) ±20 %
Miscellaneous						
Operating temperature range	-20 to 80	-20 to 80	-20 to 80	-20 to 80	°C	
Material	Aluminum	Aluminum	Aluminum	Aluminum		
Mass	0.58	0.675	0.58	0.675	kg	±5 %
Cable length	1.5	1.5	1.5	1.5	m	±10 mm
Sensor/ voltage connection	Sub-D special (CD-version) LEMO LEMO (CL-version)	Sub-D special (CD-version) (CL-version)	Sub-D special	Sub-D special		

*With digital controller. Non-linearity of direct drive stages measured with analog controllers is up to 0.1 % typ.

Recommended controller:
Single-channel (1 per axis): E-610 servo controller / amplifier (p. 2-110), E -625 servo controller, bench-top (p. 2-114), E-621 controller module (p. 2-160)
Multi-channel: modular piezo controller system E-500 (p. 2-142) with amplifier module E-503 (three channels) (p. 2-146) or E-505 (1 per axis, high-power) (p. 2-147) and E-509 controller (p. 2-152)
Multi-channel digital controllers: E-710 bench-top (p. 2-128), E-712 modular (p. 2-140), E-725 high-power (p. 2-126), E-761 PCI board (p. 2-130)

P-561 · P-562 · P-563 PIMars™ XYZ Piezo System

High-Precision Nanopositioning Stage, 3 to 6 Axes



P-562 PIMars™ multi-axis, parallel-kinematics nanopositioning stages are available with up to 340 µm travel per axis. Custom versions to 6 DOF are available

- **Parallel-Kinematics / Metrology for Enhanced Responsiveness / Multi-Axis Precision**
- **Travel Ranges to 340 x 340 x 340 µm**
- **Capacitive Sensors for Highest Linearity**
- **Frictionless, High-Precision Flexure Guiding System**
- **Excellent Scanning Flatness**
- **High-Dynamics XYZ Version Available; Custom Versions to 6-DOF**
- **Clear Aperture 66 x 66 mm**
- **Outstanding Lifetime Due to PICMA® Piezo Actuators**
- **UHV Versions to 10^{-9} hPa**

PIMars™ open-frame piezo stages are fast and highly accurate multi-axis scanning and nanopositioning systems with flatness and straightness in the nanometer range.

The 66 x 66 mm clear aperture is ideal for transmitted-light applications such as near -field scanning or confocal micro - scopy and mask positioning.

Large Variety of Models

PIMars™ multi-axis nanopositioners are offered in a large variety of configurations. Standard models include long-travel systems (to 300 x 300 x 300 µm), high-speed and vacuum versions. Custom six-axis designs with rotation to 6 mrad are available on request.

PI offers versions specially designed for applications in ultra-high vacuum with vacuum-qualified components only. The integrated ceramic-encapsulated PICMA ® actuators allow high bakeout tempera - tures and assure minimal outgassing rates. A non-magnetizable version is available on request.

Application Examples

- Scanning microscopy
- Mask/wafer positioning
- Interferometry
- Metrology
- Biotechnology
- Micromanipulation

Direct Drive for Ultra-Fast Scanning and Positioning

The P-561.3DD versions have resonant frequencies to 1.0 kHz, enabling millisecond scanning rates with sub-nanometer resolution.

Capacitive Sensors for Highest Accuracy and Position Stability

PI's proprietary capacitive sensors measure position directly and without physical contact. They are free of friction and hysteresis, a fact which, in combination with the positioning resolution of well under 1 nm, makes it possible to achieve very high levels of linearity. A further advantage of direct metrology with capacitive sensors is the high phase fidelity and the high bandwidth of up to 10 kHz.

Active and Passive Guidance for Nanometer Flatness and Straightness

Wire-cut flexures optimized with Finite Element Analysis (FEA) are used to guide the stage. The FEA techniques give the design the highest possible stiffness and minimize linear and angular runout. Further enhancement is achieved by active trajectory control: multi

Ordering Information

P-561.3CD
PIMars™ XYZ Piezo-Nanopositioning System, 100 x 100 x 100 µm, Parallel Metrology

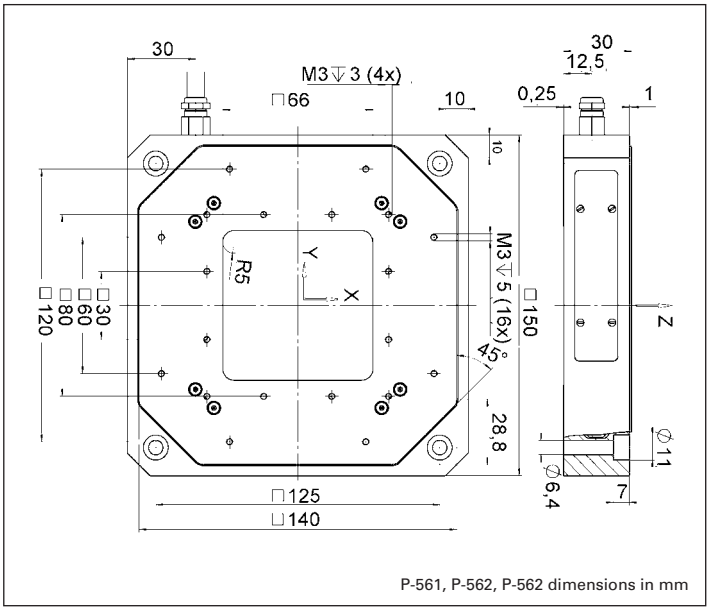
P-562.3CD
PIMars™ XYZ Piezo-Nanopositioning System, 200 x 200 x 200 µm, Parallel Metrology

P-563.3CD
PIMars™ XYZ Piezo-Nanopositioning System, 300 x 300 x 300 µm, Parallel Metrology

P-561.3DD
PIMars™ High-Dynamics XYZ Nanopositioning System, 45 x 45 x 15 µm, Parallel Metrology, Direct Drive

Vacuum-compatible versions to 10^{-6} hPa for the P-561.3CD, P-562.3CD and P-563.3CD models are available as P-561.3VD, P-562.3VD and P-563.3VD; versions to 10^{-9} hPa as P-561.3UD, P-562.3UD and P-563.3UD.

Super-invar & titanium versions are available, 6-DOF versions on request.



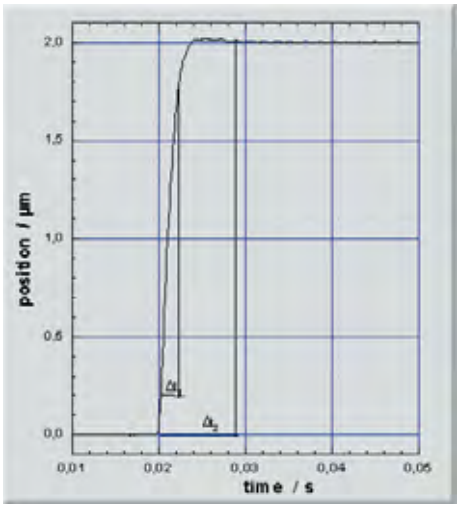
P-561, P-562, P-562 dimensions in mm

System properties

System Configuration	P-561.3CD with E-710 digital controller, 330 g load
Amplifier bandwidth, small signal	25 Hz in X, Y; 35 Hz in Z
Settling time (10 % step)	20 ms

axis nanopositioning systems equipped with parallel metrology are able to measure platform position in all degrees of freedom against a common, fixed reference. In such systems, undesirable motion from one actuator in the direction of another (cross-talk) is detected immediately and actively compensated by the servo-loops. This can keep deviation from a trajectory to under a few nano - meters, even in dynamic operation.

P-562.3CD (unloaded) step and settle is faster than 10 ms in X, Y and Z



E-725 Digital 3-channel controller with nanopositioning system

Technical Data

Model	P-561.3CD	P-562.3CD	P-563.3CD	P-561.3DD	Units	Tolerance
Active axes	X, Y, Z	X, Y, Z	X, Y, Z	X, Y, Z		
Motion and positioning						
Integrated sensor	Capacitive	Capacitive	Capacitive	Capacitive		
Open-loop travel, -20 to +120 V	150 x 150 x 150	300 x 300 x 300	340 x 340 x 340	58 x 58 x 18	µm	min. (+20 %/0 %)
Closed-loop travel	100 x 100 x 100	200 x 200 x 200	300 x 300 x 300	45 x 45 x 15	µm	
Open-loop resolution	0.2	0.4	0.5	0.1	nm	typ.
Closed-loop resolution	0.8	1	2	0.2	nm	typ.
Linearity	0.03	0.03	0.03	0.01*	%	typ.
Repeatability in X, Y, Z	2 / 2 / 2	2 / 2 / 4	2 / 2 / 4	2 / 2 / 2	nm	typ.
Pitch in X,Y	±1	±2	±2	±3	µrad	typ.
Runout θ_x, θ_y (Z motion)	±15	±20	±25	±3	µrad	typ.
Yaw in X, Y	±6	±10	±10	±3	µrad	typ.
Flatness in X, Y	±15	±20	±25	±10	nm	typ.
Crosstalk X, Y (Z motion)	±30	±50	±50	±20	nm	typ.
Mechanical properties						
Unloaded resonant frequency in X / Y / Z	190 / 190 / 380	160 / 160 / 315	140 / 140 / 250	920 / 920 / 1050**	Hz	±20 %
Resonant frequency @ 100 g in X / Y / Z	-	145 / 145 / 275	120 / 120 / 215	860 / 860 / 950	Hz	±20 %
Resonant frequency @ 30 g in X / Y / Z	140 / 140 / 300	130 / 130 / 195	110 / 110 / 170	500 / 500 / 470	Hz	±20 %
Push force capacity in motion direction in X / Y / Z	200 / 200 / 50	120 / 120 / 50	100 / 100 / 50	200 / 200 / 50	N	Max.
Pull force capacity in motion direction in X / Y / Z	30 / 30 / 30	30 / 30 / 30	30 / 30 / 30	30 / 30 / 30		
Load capacity	50	50	50	50	N	Max.
Drive properties						
Ceramic type	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885 in Z, P-888 in XY		
Electrical capacitance in X / Y / Z	5.2 / 5.2 / 10.4	7.4 / 7.4 / 14.8	7.4 / 7.4 / 14.8	38 / 38 / 6	µF	±20 %
Dynamic operating current coefficient (DOCC) in X / Y / Z	6.5 / 6.5 / 13	4.6 / 4.6 / 9.25	3.1 / 3.1 / 6.1	106 / 106 / 50	µA/ (Hz • µm)	±20 %
Miscellaneous						
Operating temperature range	-20 to 80	-20 to 80	-20 to 80	-20 to 80	°C	
Material	Aluminum	Aluminum	Aluminum	Aluminum		
Mass	1.45	1.45	1.45	1.55	kg	±5 %
Cable length	1.5	1.5	1.5	1.5	m	±10 mm
Sensor / voltage connection	Sub-D Special	Sub-D Special	Sub-D Special	Sub-D Special		

Resolution of PI Piezo Nanopositioners is not limited by friction or stiction. V alue given is noise equivalent motion with E-71 0 (p. 2-128) controller.
*With digital controller. Non-linearity of direct drive stages measured with analog controllers is typically up to 0.1 %.

Recommended controller
Multi-channel digital controllers: E-710 bench-top (p. 2-128), E-712 modular (p. 2-140), E-725 high-power (p. 2-126), E-761 PCI board (p. 2-130)

Ultra-Long Travel PIHera® Planar XY Piezo Stage

High-Precision Nanopositioner Family–Compact and Long Travel Ranges

PIHera® XY-Nanopositioniersysteme mit Stellwegen von 50 x 50 µm bis 1800 x 1800 µm

- **Travel Ranges 50 to 1800 µm**
- **High-Precision, Cost-Efficient**
- **Resolution to 0.1 nm**
- **Frictionless, High-Precision Flexure Guiding System**
- **0,02 % Positioning Accuracy**
- **Outstanding Lifetime Due to PICMA® Piezo Actuators**
- **X-, XY-, Z- and XYZ-Versions**
- **Vacuum-Compatible Versions Available**

Two-axis (XY) PIHera® systems are piezo-nanopositioning stages featuring travel ranges from 50 to 1800 µm. Despite the increased travel ranges, the units are extremely compact and provide rapid response and high guiding precision. This, and the long travel range is achieved with a friction-free and extremely stiff flexure system sub-nanometer resolution. The PIHera® piezo nanopositioning series also includes Z and X stages (see p. 2-22 and p. 2-40).

Application Examples

- Interferometry
- Microscopy
- Nanopositioning
- Biotechnology
- Quality assurance testing
- Semiconductor technology

Nanometer Precision in Milliseconds

One of the advantages of PIHera® stages over motor-driven positioning stages is the rapid response to input changes and the fast and precise settling behavior. The P-622.1CD, for example, can settle to an accuracy of 10 nm in only 30 msec (other PI stages provide even faster response)!

Superior Accuracy With Direct-Metrology Capacitive Sensors

A choice of tasks such as optical path adjustment in interferometry, sample positioning in microscopy, precision alignment or optical tracking require the relatively long scanning ranges and nanometer precision offered by PIHera® nanopositioning stages.
PI's proprietary capacitive sensors measure position directly and without physical contact. They are free of friction and hysteresis, a fact which, in combination with the positioning resolution of well under 1 nm, makes it possible to achieve very high levels of linearity. A further advantage of direct metrology with capacitive sensors is the high phase fidelity and the high bandwidth of up to 10 kHz.

Designed for Precision

High stiffness is achieved with the FEA-optimized design of the frictionless flexure elements, which assure excellent guiding accuracy and dynamics. A straightness and flatness in the nanometer range is achieved.

Ordering Information

P-620.2CD* / P-620.2CL*
PIHera® Precision XY Nanopositioning System, 50 x 50 µm, Direct Metrology, Capacitive Sensors

P-621.2CD* / P-621.2CL*
PIHera® Precision XY Nanopositioning System, 100 x 100 µm, Direct Metrology, Capacitive Sensors

P-622.2CD* / P-622.2CL*
PIHera® Precision XY Nanopositioning System, 250 x 250 µm, Direct Metrology, Capacitive Sensors

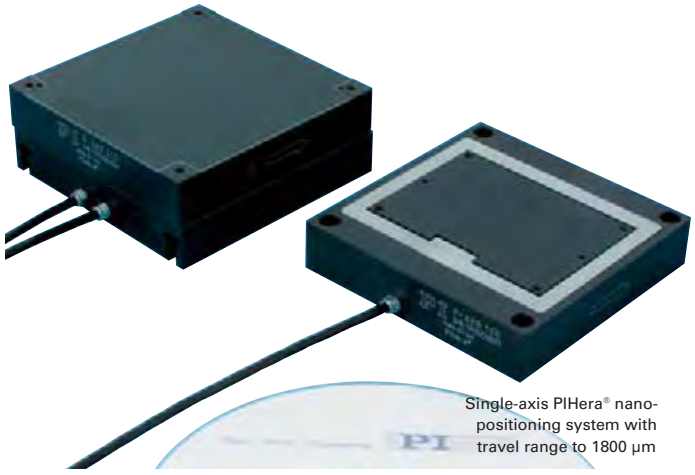
P-625.2CD* / P-625.2CL*
PIHera® Precision XY Nanopositioning System, 500 x 500 µm, Direct Metrology, Capacitive Sensors

P-628.2CD* / P-628.2CL*
PIHera® Precision XY Nanopositioning System, 800 x 800 µm, Direct Metrology, Capacitive Sensors

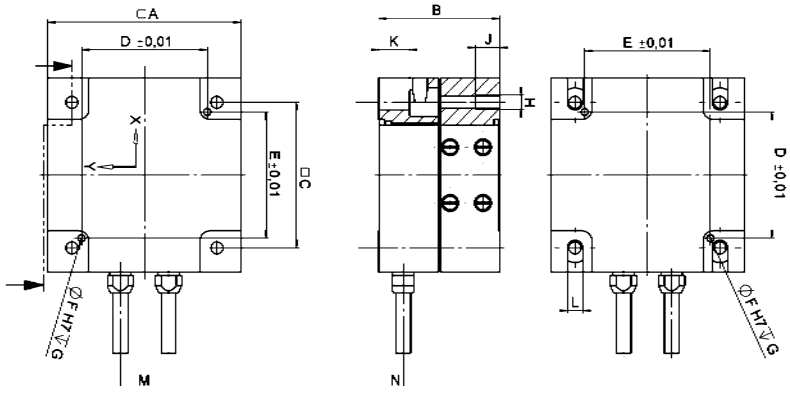
P-629.2CD* / P-629.2CL*
PIHera® Precision XY Nanopositioning System, 1500 x 1500 µm, Direct Metrology, Capacitive Sensors

*.2CD with Sub-D Connector
*.2CL with LEMO Connector

Open-loop versions are available as P-62x.20L.
Vacuum versions to 10^{-9} hPa are available as P-62x.2UD.



Single-axis PIHera® nanopositioning system with travel range to 1800 µm



	A	B	C	D	E	ØF	G
P-620.2CD / .20L	30	21,5	24	24	19	1,01	1,5
P-621.2CD / .20L	40	25	30	26	26	1,51	2,5
P-622.2CD / .20L	50	25	40	35	35	1,51	2,5
P-625.2CD / .20L	60	25	50	46	46	1,51	2,5
P-628.2CD / .20L	80	30	70	66	66	1,51	2,5

	H	J	K	L	M	N
P-620.2CD / .20L	M2	3,5	5,1	2,2	9	6
P-621.2CD / .20L	M3	5	6,25	3,2	10	5
P-622.2CD / .20L	M3	5	6,25	3,2	11	5
P-625.2CD / .20L	M3	6	6,25	3,2	11	5
P-628.2CD / .20L	M3	6	6,75	3,2	11	5

P-62x.2CD/.2CL/.20L Abmessungen in mm

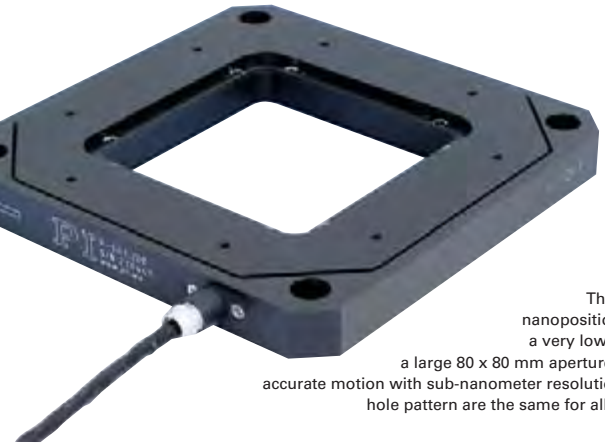
Technical Data

Model	P-620.2CD/ P-620.2CL	P-621.2CD/ P-621.2CL	P-622.2CD/ P-622.2CL	P-625.2CD/ P-625.2CL	P-628.2CD/ P-628.2CL	P-629.2CD P-629.2CL	P-62x.20L open-loop versions	Units T	olerance
Active axes	X, Y	X, Y	X, Y	X, Y	X, Y	X, Y	X, Y		
Motion and positioning									
Integrated sensor	Capacitive	Capacitive	Capacitive	Capacitive	Capacitive	Capacitive	–		
Open-loop travel X, Y, -20 to +120 V	60	120	300	600	950	1800	as P-62x.2CD	µm	min. (+20 %/-0 %)
Closed-loop travel	50	100	250	500	800	1500	–	µm	
Open-loop resolution	0.1	0.2	0.4	0.5	0.5	2	as P-62x.2CD	nm	typ.
Closed-loop resolution	0.2	0.4	0.7	1.4	3.5	3.5	–	nm	typ.
Linearity 0.02		0.02	0.02	0.03	0.03	0.03	–	%	typ.
Repeatability ±2		±2	±2	±5	±10	±14	as P-62x.2CD	nm	typ.
Pitch / yaw	±3	±3	±3	±3	±20	±30	as P-62x.2CD	µrad	typ.
Mechanical properties									
Stiffness	0.22	0.25	0.2	0.1	0.05	0.1	as P-62x.2CD	N/µm	±20 %
Unloaded resonant frequency in X,	575	420	225	135	75	60	as P-62x.2CD	Hz	±20 %
Unloaded resonant frequency in Y	800	535	300	195	105	100	as P-62x.2CD	Hz	±20 %
Resonant frequency in X @ 50 g	270	285	180	120	60	55	as P-62x.2CD	Hz	±20 %
Resonant frequency in Y @ 50 g	395	365	215	150	85	85	as P-62x.2CD	Hz	±20 %
Resonant frequency in X @ 100 g	285	220	160	105	55	50	as P-62x.2CD	Hz	±20 %
Resonant frequency in Y @ 100 g	300	285	175	125	75	80	as P-62x.2CD	Hz	±20 %
Push/pull force capacity in motion direction	10 / 5	10 / 8	10 / 8	10 / 8	10 / 8	10 / 8	as P-62x.2CD	N	Max.
Load capacity	10	10	10	10	10	10	as P-62x.2CD	N	Max.
Lateral Force	10	10	10	10	10	10	as P-62x.2CD	N	Max.
Drive properties									
Ceramic type	PICMA® P-883	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-887	PICMA® P-888	as P-62x.2CD		
Electrical Capacitance	0.35	1.5	3.1	6.2	19	52	as P-62x.2CD	µF	±20 %
Dynamic operating current coefficient	0.9	1.9	1.9	1.6	3	4.3	as P-62x.2CD	µA/(Hz•µm)	±20 %
Miscellaneous									
Operating temperature range	-20 to 80	-20 to 80	-20 to 80	-20 to 80	-20 to 80	-20 to 80	-20 to 150	°C	
Material	Aluminum	Aluminum	Aluminum	Aluminum	Aluminum	Aluminum	Aluminum		
Mass	0.195	0.295	0.348	0.43	0.7	1.37	as P-62x.2CD	kg	±5 %
Cable length	1.5	1.5	1.5	1.5	1.5	1.5	1.5	m	±10 mm
Sensor / voltage connection	CD version: 2x Sub-D special CL version: LEMO	CD version: 2x Sub-D special CL version: LEMO	CD version: 2x Sub-D special CL version: LEMO	CD version: 2x Sub-D special CL version: LEMO	CD version: 2x Sub-D special CL version: LEMO	CD version: 2x Sub-D special CL version: LEMO	2x LEMO (no sensor)		

Lower axis: X; upper axis: Y.
Resolution of PI Piezo Nanopositioners is not limited by friction or stiction. The value given is noise equivalent motion with E-710 controller (p. 2-128)
Recommended controller
CD version: E-610 servo controller / amplifier (p. 2-110), E-625 servo controller , bench-top (p. 2-114), E-665 powerful servo c ontroller, bench-top (p. 2-116)
Multi-channel digital controllers: E-710 bench-top (p. 2-128), E-712 modular (p. 2-140), E-725 high-power (p. 2-126), E-761 PCI board (p. 2-140)
CL version: E-500 modular piezo controller system (p. 2-142) with E-505 amplifier module (1 per axis, high power) (p. 2-147) and E-509 controller (p. 2-152)
Open-loop versions: E-500 modular piezo controller system (p. 2-142) with E-505 amplifier module (1 per axis, high power) (p. 2- 147)

P-541.2 – P-542.2 Planar Piezo XY-Stage

Low-Profile XY Nanopositioning System with Large Aperture



The P-541/P-542-series nanopositioning stages feature a very low profile of 16.5 mm, a large 80 x 80 mm aperture and deliver highly accurate motion with sub-nanometer resolution. Dimensions and hole pattern are the same for all P-541/P-542 stages

- **Low Profile for Easy Integration: 16.5 mm; 80 x 80 mm Clear Aperture**
- **Up to 200 x 200 µm Travel Range**
- **Parallel-Kinematics / Metrology for Enhanced Responsiveness & Multi-Axis Precision**
- **High-Dynamics Direct-Drive Version**
- **Choice of Sensors: Strain Gauge (Lower Cost) or Capacitive Sensors (Higher Performance)**
- **Outstanding Lifetime Due to PICMA® Piezo Actuators**
- **Combination with Long Travel Microscopy Stages or Longer Stroke**

Low Profile, Optimized for Microscopy Applications

P-541/P-542 nanopositioning and scanning stages are designed for easy integration into high-resolution microscopes. They feature a very low profile of 16.5 mm, a large 80 x 80 mm aperture, and offer highly accurate motion with sub-nanometer resolution. A variety of Z stages and Z-tip/tilt stages with the same footprint are also offered to suit a wide range of applications (p. 2-44). They are ideal for alignment, nano-focusing or metrology tasks.

Choice of Drives: Long Range or High-Speed Direct Drive

Lever-amplified XY systems with 100 and 200 µm travel and direct-driven XY scanners with 45 µm travel are available. Their high resonant frequencies of 1.5 kHz in both axes allow for faster step response and higher scanning rates, needed for example in single-molecule microscopy, or in other time-critical applications.

Parallel Kinematics for Fast Response

In a parallel kinematics multi-axis system, all actuators act directly on one moving platform. This means that all axes move the same minimized mass and can be designed with identical dynamic properties. Systems with parallel kinematics and metrology have additional advantages over serially stacked or nested systems, including more-compact construction and no cumulative error from the different axes.

Parallel kinematics systems can be operated with up to six degrees of freedom with low inertia and excellent dynamic performance. Multi-axis nanopositioning systems equipped with both parallel kinematics and parallel, direct metrology are able to measure platform position in all degrees of freedom against one common fixed reference. In such systems, undesirable motion from one actuator in the direction of another (cross talk) is detected immediately and actively compensated by the servo-loops.

Tailored Position Measurement

Integrated high-resolution position sensors provide fast response and positional stability in the nanometer range. Top-of-the-line models use capacitive sensors. They measure displacement directly and without physical contact (direct metrology) enabling superior linearity.

Alternatively, versions with cost-effective strain gauge sensors (SGS) are also available.

Application Examples

- Laser technology
- Scanning microscopy
- Mask / wafer positioning
- Interferometry
- Metrology
- Biotechnology
- Micromanipulation

Ordering Information

P-541.2DD
XY Nanopositioning System with large Aperture, High-Speed Direct Drive, 45 x 45 µm, Parallel Kinematics, Capacitive Sensors

P-541.2CD
XY Nanopositioning System with large Aperture, 100 x 100 µm, Parallel Kinematics, Capacitive Sensors

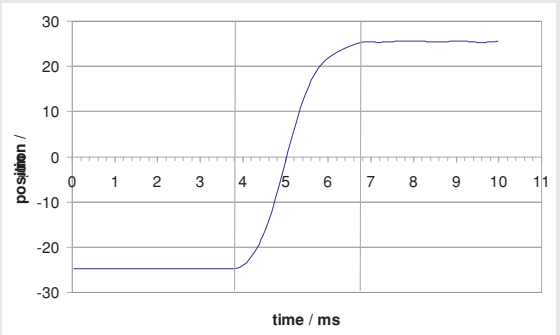
P-542.2CD
XY Nanopositioning System with large Aperture, 200 x 200 µm, Parallel Kinematics, Capacitive Sensors

P-541.2SL
XY Nanopositioning System with large Aperture, 100 x 100 µm, Strain Gauge Sensors

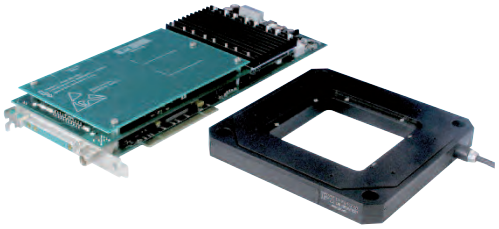
P-542.2SL
XY Nanopositioning System with large Aperture, 200 x 200 µm, Strain Gauge Sensors

P-541.20L
XY Nanopositioning System with large Aperture, 100 x 100 µm, Open Loop

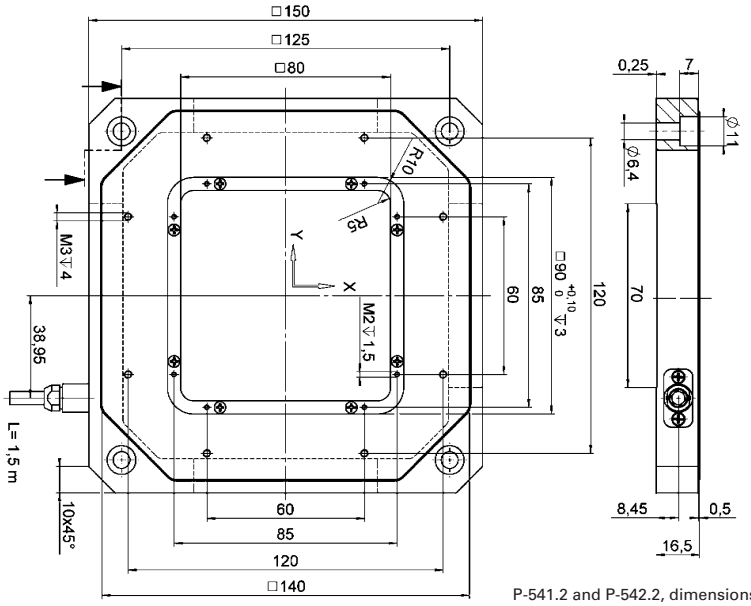
P-542.20L
XY Nanopositioning System with large Aperture, 200 x 200 µm, Open Loop



The settling time of a P-541.2DD stage is only 3 ms for a 50 µm step



The digital E-761 nanopositioning controller as PC Plug-in card presents a low-cost alternative to the tabletop or rack-mounting version with casings.



P-541.2 and P-542.2, dimensions

E-725 Digital 3-channel controller with nanopositioning system

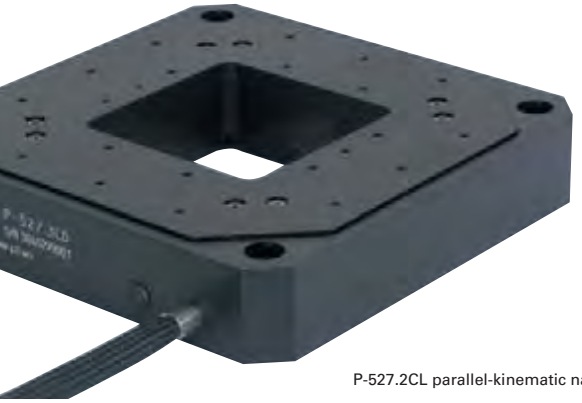
Technical Data

Model	P-541.2CD	P-542.2CD	P-541.2DD	P-541.2SL	P-542.2SL	P-541.20L	P-542.20L	Units	Tolerance
Active axes	X, Y	X, Y	X, Y	X, Y	X, Y	X, Y	X, Y		
Motion and positioning									
Integrated sensor	Capacitive	Capacitive	Capacitive	SGS	SGS	–	–		
Open-loop travel, -20 to +120 V	175 x 175	290 x 290	60 x 60	175 x 175	290 x 290	175 x 175	290 x 290	µm	min. (+20 %/0 %)
Closed-loop travel	100 x 100	200 x 200	45 x 45	100 x 100	200 x 200	–	–	µm	
Closed-loop / open-loop resolution	0.2 / 0.3	0.4 / 0.7	0.1 / 0.3	0.2 / 2.5	0.4 / 4	0.2 / –	0.4 / –	nm	typ.
Linearity 0.03		0.03	0.03*	0.2	0.2	–	–	%	typ.
Repeatability <5		<5	<5	<10	<10	–	–	nm	typ.
Pitch	<±5	<±5	<±3	<±5	<±5	<±5	<±5	µrad	typ.
Yaw	<±10	<±10	<±3	<±10	<±10	<±10	<±10	µrad	typ.
Mechanical properties									
Stiffness in motion direction	0.47	0.4	10	0.47	0.4	0.47	0.4	N/µm	±20 %
Unloaded resonant frequency	255	230	1550	255	230	255	230	Hz	±20 %
Resonant frequency @ 100 g	200	190	–	200	190	200	190	Hz	±20 %
Resonant frequency @ 200 g	180	–	1230	180	–	180	–	Hz	±20 %
Resonant frequency @ 300 g	150	145	–	150	145	150	145	Hz	±20 %
Push/pull force capacity in motion direction	100 / 30	100 / 30	100 / 30	100 / 30	100 / 30	100 / 30	100 / 30	N	Max.
Load capacity	20	20	20	20	20	20	20	N	Max.
Drive properties									
Ceramic type	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885		
Electrical capacitance per axis	4.2	7.5	9	4.2	7.5	4.2	7.5	µF	±20 %
Dynamic operating current coefficient per axis	5.2	4.8	25	5.2	4.8	5.2	4.8	µA/(Hz•µm)	±20 %
Miscellaneous									
Operating temperature range	20 to 80	20 to 80	20 to 80	-20 to 80	-20 to 80	-20 to 80	-20 to 80	°C	
Material	Aluminum	Aluminum	Aluminum	Aluminum	Aluminum	Aluminum	Aluminum		
Mass	1100	1150	1210	1050	1100	1050	1100	kg	±5 %
Cable length	1.5	1.5	1.5	1.5	1.5	1.5	1.5	m	±10 mm
Sensor connection	Sub-D Special	Sub-D Special	Sub-D Special	LEMO	LEMO	–	–		
Voltage connection	Sub-D Special	Sub-D Special	Sub-D Special	LEMO	LEMO	LEMO	LEMO		

Resolution of PI Piezo Nanopositioners is not limited by friction or stiction. V alue given is noise equivalent motion with E-50 3 (p. 2-146) or E-710 controller (p. 2-128).
Dynamic Operating Current Coefficient in µA per Hz and µm. Example: Sinusoidal scan of 10 µm at 10 Hz requires approximately 0. 48 mA drive current for the P-542.2CD.
*With digital controller. Non-linearity of direct drive stages measured with analog controllers is up to 0.1 % typ.
Recommended controller / amplifier
Single-channel (1 per axis): E-610 servo controller / amplifier (p. 2-110), E-625 servo controller , bench-top (p. 2-114), E-621 controller module (p. 2-160)
Multi-channel: modular piezo controller system E-500 (p. 2-142) with amplifier module E-503 (three channels) (p. 2-146) or E-505 (1 per axis, high-power) (p. 2-147) and E-509 controller (p. 2-152) (for systems with sensors)
Multi-channel digital controllers: E-710 bench-top (p. 2-128), E-712 modular (p. 2-140), E-725 high-power (p. 2-126), E-761 PCI board (p. 2-130)

P-517 · P-527 Planar Multi-Axis Piezo Scanner

High-Dynamics Nanopositioner / Scanner with Direct Position Metrology



P-527.2CL parallel-kinematic nanopositioning system

- **Travel Ranges to 200 µm**
- **Sub-Nanometer Resolution**
- **Frictionless, High-Precision Flexure Guiding System**
- **Capacitive Sensors for Highest Linearity**
- **Parallel-Kinematics / Metrology for Enhanced Responsiveness / Multi-Axis Precision**
- **Clear Aperture 66 x 66 mm**
- **Outstanding Lifetime Due to PICMA® Piezo Actuators**

P-517 and P-527 high-dynamics, multi-axis piezo-nanopositioning stages are available in XY ΘZ, XY and XYZ configurations featuring linear travel ranges to 200 x 200 x 20 µm and rotation ranges to 4 mrad. The 66 x 66 mm clear aperture is ideal for transmitted-light applications.
Z/tip/tilt versions in the same form factor are also offered as models P-518, P-528, P-558 (see p. 2-46) and as custom versions with up to six degrees of freedom.

Capacitive Sensors for Highest Accuracy

PI's proprietary capacitive sensors measure position directly and without physical contact. They are free of friction and hysteresis, a fact which, in combination with the positioning resolution of well under 1 nm, makes it possible to achieve very high levels of linearity. A further advantage of direct metrology with capacitive sensors is the high phase fidelity and the high bandwidth of up to 10 kHz.

Application Examples

- Metrology
- Interferometry
- Optics
- Lithography
- Nanopositioning
- Scanning microscopy
- Mass storage device testing
- Laser technology
- Micromachining

Technical Data

Models	P-517.2CL	P-527.2CL	P-517.3CL/ P-527.3CL/ P-517.3CD P-527.3CD		P-517.RCD	P-527.RCD
Active axes	X, Y	X, Y	X, Y, Z	X, Y, Z	X, Θ_Y, Θ_Z	Θ_Y, Θ_Z
Motion and positioning						
Integrated sensor	Capacitive	Capacitive	Capacitive	Capacitive	Capacitive	Capacitive
Open-loop travel, -20 to +120 V	130	250	130; Z: 25	250; Z: 25	130; Θ_Z: ±1.3 mrad	250; Θ_Z: ±2.5 mrad
Closed-loop travel	100	200	100; Z: 20	200; Z: 20	100; Θ_Z: ± 1 mrad	200; Θ_Z: ± 2 mrad
Open-loop resolution	0.3	0.5	0.3; Z: 0.1	0.5; Z: 0.1	0.3; Θ_Z: 0.1 µrad	0.5; Θ_ZZ: 0.1 µrad
Closed-loop resolution	1	2	1; Z: 0.1	2; Z: 0.1	1; Θ_Z: 0.3 µrad	2; Θ_Z: 0.3 µrad
Linearity	0.03	0.03	0.03	0.03	0.03	0.03
Repeatability	±5	±10	±5; Z: ±1	±10; Z: ±1	±5; Z: ±0.5 µrad	±10
Mechanical properties						
Stiffness	2	1	2; Z: 15	1; Z: 15	2	1
Unloaded resonant frequency	450	350	450; Z: 1100	350; Z: 1100	450; Z: 400	350; Z: 300
Resonant frequency @ 500 g X, Y	250	190	250	190	250	190
Resonant frequency @ 2500 g X, Y	140	110	140	110	140	110
Push/pull force capacity in motion direction	50 / 30	50 / 30	50 / 30	50 / 30	50 / 30	50 / 30
Drive properties						
Ceramic type	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885
Electrical capacitance	9.2	9.2	9; Z: 6	9; Z: 6	9	9
Dynamic operating current coefficient (DOCC)	11.5	5.8	11.5; Z: 37	5.5; Z: 37	11.5	5.5
Miscellaneous						
Operating temperature range	-20 to 80	-20 to 80	-20 to 80	-20 to 80	-20 to 80	-20 to 80
Material	Aluminum	Aluminum	Aluminum	Aluminum	Aluminum	Aluminum
Mass	0.14	0.14	0.145	0.145	0.14	0.14
Sensor / voltage connection	LEMO	LEMO	Sub-D special (CD-version) LEMO (CL-version)	; Sub-D special (CD-version) LEMO (CL-version)	Sub-D Special	Sub-D Special

Resolution of PI Piezo Nanopositioners is not limited by friction or stiction. Value given is noise equivalent motion with E -503 or E-710 controller (p. 2-146 or p. 2-128)
Linear Dynamic Operating Current Coefficient in µA per Hz and µm. Example for P-527.2xx: Sinusoidal scan of 30 µm at 10 Hz requires approximately 1.8 mA drive current (p. 2-70). Electrical capacitance and DOCC of the rotati
stated.
Recommended controller
Versions with LEMO connectors: Single-channel (1 per axis): E-610 servo-controller / amplifier (p. 2-110), E-625 servo-controller, bench-top (p. 2-114), E-621 controller module (p. 2-160) Multi-channel: modular piezo controller sy
(three channels) (p. 2-146) or E-505 (1 per axis, high-power) (p. 2-147) and E-509 controller (p. 2-152)
Versions with Sub-D connectors: Multi-channel digital controllers: E-710 bench-top (p. 2-128), E-712 modular (p. 2-140), E-72 5 high-power (p. 2-126), E-761 PCI board (p. 2-130)

Active and Passive Guidance for Nanometer Flatness and Straightness

Flexures optimized with Finite Element Analysis (FEA) are used to guide the stage. The FEA techniques provide for the highest possible stiffness in, and perpendicular to, the direction of motion, and minimize linear and angular runout. Flexures allow extremely high-precision motion, no matter how minute, as they are completely free of play and friction. Due to the parallel kinematics design there is only one common moving platform for all axes, minimizing mass, enabling identical dynamic behavior and eliminating cumulative errors. Parallel kinematics also allows for a more compact construction and faster response compared to stacked or nested designs. The high precision due to flexure guidance is further enhanced by Active T rajectory Control: Multi-axis nanopositioning systems equipped with both parallel kinematics and parallel direct metrology are able to measure platform position in all degrees of freedom against one common fixed reference. In such systems, undesirable motion from one actuator in the direction of another (cross-talk) is detected immediately and actively compensated by the servo-loops. This Active T rajectory Control Concept can keep deviation from a trajectory to under a few nanometers, even in dynamic operation.

Ceramic Insulated Piezo Actuators Provide Long Lifetime

Highest possible reliability is assured by the use of award-winning PICMA® multilayer piezo actuators. PICMA® actuators are the only actuators on the market with ceramic-only insulation, which makes them resistant to ambient humidity and leakage-current failures. They are thus far superior to conventional actuators in reliability and lifetime.

	Units	Tolerance
	µm	min.(+20%/0%)
	µm	
	nm	typ.
	nm	typ.
	%	typ.
	nm	typ.
	N/µm	±20%
	Hz	±20%
	Hz	±20%
	Hz	±20%
	N	Max.
	µF	±20%
	µA/(Hz • µm)	±20%
	°C	
	kg	±5%

on axes base upon differential motion in X, Y; therefore not

stem E-500 (p. 2-142) with amplifier module E-503

Ordering Information

P-517.2CL
Precision XY Nanopositioning System, 100 x 100 µm, Capacitive Sensors, Parallel Metrology, LEMO Connector

P-527.2CL
Precision XY Nanopositioning System, 200 x 200 µm, Capacitive Sensors, Parallel Metrology, LEMO Connector

P-517.3CL
Precision XYZ Nanopositioning System, 100 x 100 x 20 µm, Capacitive Sensors, Parallel Metrology, LEMO Connector

P-517.3CD
Precision XYZ Nanopositioning System, 100 x 100 x 20 µm, Capacitive Sensors, Parallel Metrology, Sub-D Connector

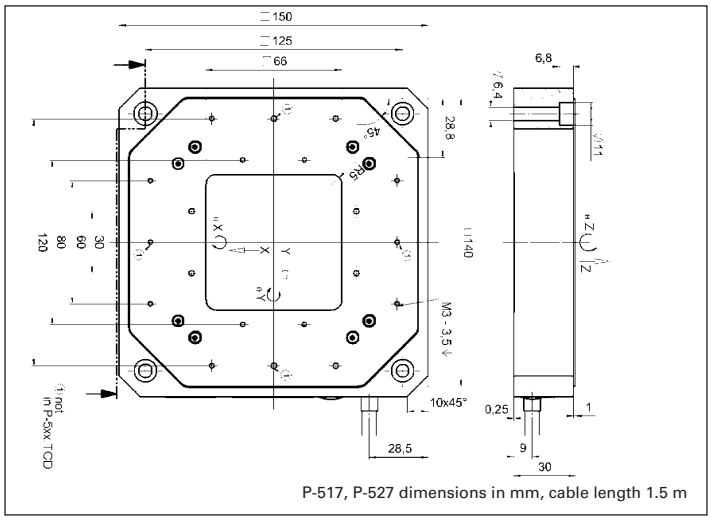
P-527.2CL
Precision XY Nanopositioning System, 200 x 200 µm, Capacitive Sensors, Parallel Metrology, LEMO Connector

P-527.3CD
Precision XYZ Nanopositioning System, 200 x 200 x 20 µm, Capacitive Sensors, Parallel Metrology, Sub-D Connector

P-517.RCD
Precision XY / rotation nanopositioning system, 100 x 100 µm, 2 mrad, Capacitive Sensors, Parallel Metrology, Sub-D Connector

P-527.RCD
Precision XY / rotation nanopositioning system, 200 x 200 µm, 4 mrad, Capacitive Sensors, Parallel Metrology, Sub-D Connector

E-725 Digital 3-channel controller with nanopositioning system



P-517, P-527 dimensions in mm, cable length 1.5 m

PInano™ Z, Scanner for SR-Microscopy

Low-Profile, Low-Cost, Nanopositioning System for Super Resolution Microscopy

PInano™ Z nanopositioning stages (shown with optional slide and Petri dish holder) feature a very low profile of 20 mm (0.8"), a large aperture and deliver highly accurate motion with sub-nanometer resolution

- **Extremely Fast Step & Settle, From 5 msec**
- **Low Profile for Easy Integration: 20 mm (0.8")**
- **100 and 200 µm Travel Ranges**
- **Proprietary Technology: Outstanding Lifetime Due to PICMA® Piezo Ceramic Stacks**
- **Cost-Effective Design due to Piezoresistive Sensors**
- **Compatible w/ Leading Image Acquisition Software Package**
- **Closed-Loop Control for High Repeatability and Accuracy**
- **USB Controller & Software Included**

High-Speed, Low Profile, Optimized for Microscopy

The new PInano™ Z low-profile piezo Z stages are optimized for very fast step and settle and easy integration into high-resolution microscope applications. They feature a very low profile of 0.8" (20 mm), a large aperture, and travel ranges of up to 200 µm with sub-nanometer closed-loop resolution–ideal for leading-edge microscopy and imaging applications.

Application Examples

- 3D Imaging
- Scanning microscopy
- Laser technology
- Interferometry
- Metrology
- Biotechnology
- Micromanipulation

Longest lifetime is guaranteed by the integrated ceramic-encapsulated PICMA® piezo actuators. Due to the significantly higher humidity resistance, the patented PICMA® design provides up to 10 times longer life than conventional piezo actuators (see latest test results at www.pi.ws/picma).

Cost Effective Design, High Performance

PInano™ series piezo positioning stages are designed to provide high performance at minimum cost. For highly-stable, closed loop operation, piezoresistive sensors are applied directly to the moving structure and precisely measure the displacement of the stage platform. The very high sensitivity of these sensors provides optimum position stability and responsiveness as well as nanometer resolution. A proprietary servo controller significantly improves the motion linearity compared to conventional piezoresistive sensor controllers.

Excellent Guiding Accuracy

Flexures optimized with Finite Element Analysis (FEA) are used to guide the stage. FEA techniques are used to give the design the highest possible stiffness in, and perpendicular to, the direction of motion, and to minimize linear and angular runout. Flexures allow extremely high-precision motion, no matter how minute, as they are completely free of play and friction.

Controller & Software Included

The PInano™ Z stage comes complete with a powerful digital closed-loop controller. The controller features two digital interfaces (USB & RS-232) as well as a high-speed analog interface and is compatible with leading image acquisition software packages such as MetaMorph etc.
The controllers are delivered including software for Windows operating systems. DLLs and LabVIEW drivers are available for automated control.
The extensive command set is based on the hardware-independent General Command Set (GCS), which is common to all current PI controllers for both nano- and micropositioning systems. GCS reduces the programming effort in the face of complex multi-axis positioning tasks or when upgrading a system with a different PI controller.

Ordering Information

P-736.ZR1S
PInano™ Z Piezo Slide Scanner System, 100 µm, Slide-Size Aperture, Piezoresistive Sensors, with USB Fully Digital Controller

P-736.ZR2S
PInano™ Z Piezo Slide Scanner System, 200 µm, Slide-Size Aperture, Piezoresistive Sensors, with USB Fully Digital Controller

Accessories

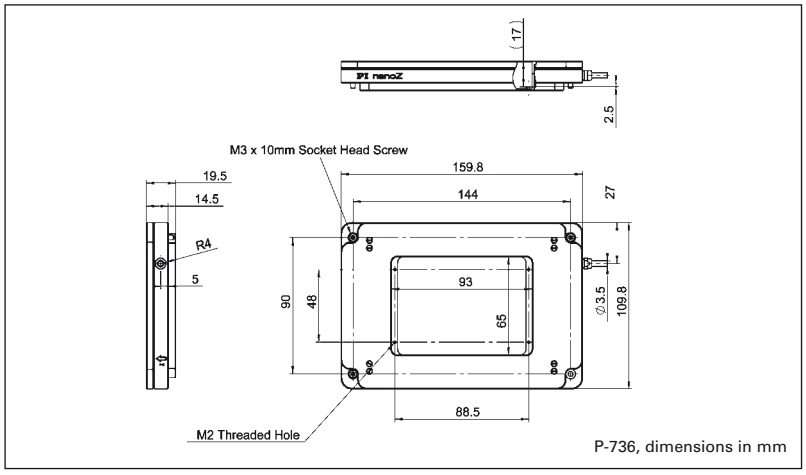
P-545.PD3
35mm Petri Dish Holder for P-545 PInano™ Piezo Stages

P-545.SH3
Microscope Slide Holder for PInano™ Piezo Stages

P-736.AP1
Adapter Plate P-736 PInano™ Piezo Z to M-545 XY Microscope Stages

The PInano™ Z stage can be combined with the M-545 high-stability, long-travel manual/motorized microscope stage (25 x 25 mm)

A compact piezo controller with a digital servo, USB, RS-232 and a high–speed analog interface is included



P-736, dimensions in mm

Technical Data

Model	P-736.ZR1S	P-736.ZR2S	Units	Tolerance
Active axes	Z	Z		
Motion and positioning				
Integrated sensor	piezoresistive	piezoresistive		
Closed-loop travel	100	200	µm	
Open-loop resolution	0.2	0.4	nm	typ.
Closed-loop resolution	0.4	0.7	nm	typ.
Linearity	±0.1	±0.1	%	typ.
Repeatability	<4	<5	nm	typ.
Mechanical properties				
Settling time (10% step width)	5	7	ms	
Load	500	500	g	max.
Drive properties				
Ceramic type	PICMA® P-885	PICMA® P-885		
Miscellaneous				
Operating temperature range	15 to 40	15 to 40	°C	
Material	Aluminum	Aluminum		
Mass	550	550	g	±5%
Cable length	1.5	1.5	m	±10 mm

N-725 PIFOC® Long Travel Scanner for Two-Photon Microscopy

1 mm Travel, Fast Response and Nanometer Precision

N-725 PIFOC® is the first piezo-objective drive with integrated NEXACT® Piezo Linear Motor, combining smooth motion, ong travel ranges and fast response with extreme position stability

- **High Force & High-Dynamics for Positioning and Scanning of Large Objectives up to 29 mm Ø**
- **1 mm Travel for Applications with Large Penetration Depth**
- **Ideal for e. g. Two-Photon Microscopy**
- **Very Fast Response: 20 ms Step and Settle Time**
- **Self Locking at Rest, no Heat Generation, no Servojitter**
- **Drive Resolution < 1 nm, 20 nm Encoder Resolution**
- **Two Motion Modes: Continuous Nanostepping and High-Dynamics Analog Mode**
- **Compact Design: Ø 48 mm, 40.5 mm Height**
- **Frictionless, High-Precision Flexure Guiding System for Better Focus Stability**
- **QuickLock Thread Adapter for Simple Installation**

The N-725 PIFOC® is the first piezo objective nanopositioner equipped with a PiezoWalk® linear motor. This drive combines smooth motion, long travel ranges and fast step and settle with extreme position stability. Its exceptional stroke of 1 mm renders stepper motor positioners -often used as range extenders for piezo drives- unnecessary. The focussing plane can be selected in an extended range without any change of the mechanics. Together with a step and settle time of less than 20 ms this allows for higher throughput.

The large travel range is a big advantage for applications that have large optical penetration depth like two-photon microscopy where it allows to make use of the full working range of the objective and quickly scan through z stacks of up to 1 mm.

Application Examples

- 3-D Imaging
- Screening
- Autofocus systems
- Microscopy
- Confocal microscopy
- Surface structure analysis
- Wafer inspection

Simple Installation with QuickLock Thread Options

The PIFOC® is mounted between the turret and the objective with the QuickLock thread adapter. After threading the adapter into the turret, the QuickLock is affixed in the desired position. Because the PIFOC® body need not to be rotated, cable wind-up is not an issue.

PiezoWalk® – the Multi-Functional Piezo Linear Motor

A great advantage characteristic of the NEXACT® drive principle is its dual-mode operating principle combining the best features of piezo motor designs, such as high resolution, high force and high speed into one compact unit. At the target position the drive requires no current and generates no heat while providing long-term, nanometer stability. This autolocking feature also completely eliminates servo jitter as it occurs with other closed-loop motors. Since motion is solely caused by the nanometer precise motion of clamped piezo actuators, there is no wear to limit the lifetime. When operated in closed-loop, excellent velocity control is achieved.

See p. 1-12 for further information on NEXACT® PiezoWalk® technology.

Controller and Drive Electronics Optimized for the Application

NEXACT® actuators require special drive electronics to control the complex stepping sequences. The E-861 includes complete NEXACT® servo controller with low-noise drivers and a powerful DSP. It also comes with ample software for easy integration and highly effective computer control. For applications which do not require the highest resolution, the E-862 lower-priced drive electronics can be ordered.

The products described in this document are in part protected by the following patents:
German Patent No. P4408618.0

Ordering Information

N-725.1A
PIFOC® Piezo Nanofocusing Z-Drive with NEXACT® Linear Motor, 1 mm, Linear Encoder, 20 nm Resolution, for QuickLock Thread Adapters

Accessories

QuickLock Thread Adapters:
see figure

P-721.90Q
Extens. Tube, 12.5 mm, Thread W0.8 x 1/36''

P-721.91Q
Extens. Tube, 12.5 mm, Thread M25 x 0.75

P-721.92Q
Extens. Tube, 12.5 mm, Thread M26 x 0.75

P-721.93Q
Extens. Tube, 12.5 mm, Thread M27 x 0.75

P-721.94Q
Extens. Tube, 12.5 mm, Thread M28 x 0.75

P-721.95Q
Extens. Tube, 12.5 mm, Thread M32 x 0.75

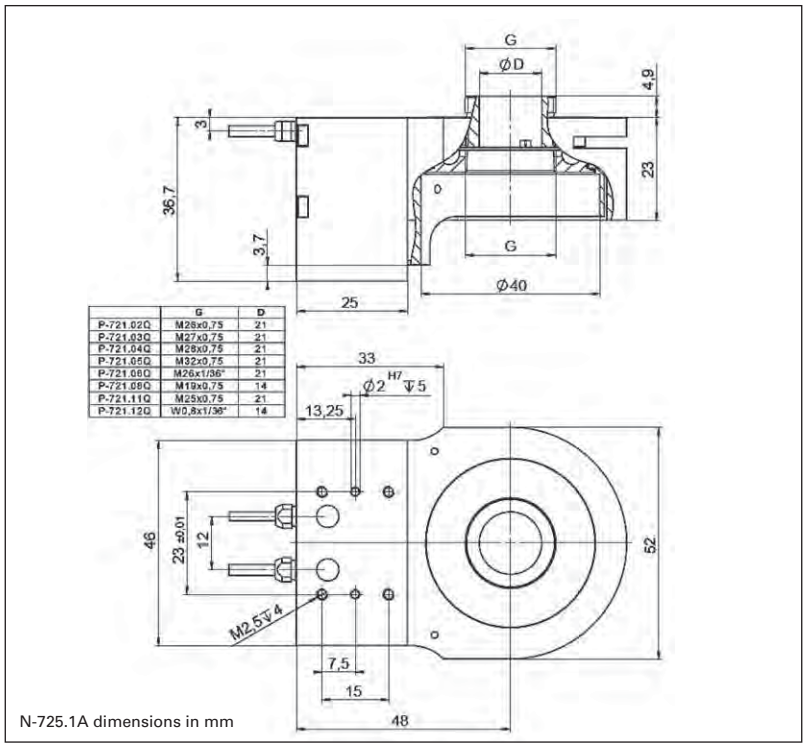
P-721.96Q
Extens. Tube, 12.5 mm, Thread M26 x 1/36''

P-721.98Q
Extens. Tube, 12.5 mm, Thread M19 x 0.75

Ask about custom designs!

Scanner for Higher Resolution and Higher Loads

PI offers a range of related PIFOC® objective scanners with different specifications. The P-725 models e. g. (s. p. 2-28) offer resolutions of less than one nanometer. For larger loads and dynamic scanning applications the models P-726 (s. p. 2-32) and P-725.DD (s. p. 2-30) are also available with travel ranges of up to 100 µm.



G	D
P-721.02Q M28x0,75	21
P-721.03Q M27x0,75	21
P-721.04Q M28x0,75	21
P-721.05Q M32x0,75	21
P-721.06Q M26x1/36"	21
P-721.09Q M19x0,75	14
P-721.11Q M25x0,75	21
P-721.12Q W0,8x1/36"	14

N-725.1A dimensions in mm

Technical Data

Model	N-725.1A
Active axes	Z
Motion and positioning	
Travel range	1 mm
Integrated sensor	Linear encoder
Sensor resolution	20 nm *
Travel range in analog mode	7 µm
Closed-loop resolution	20 nm *
Linearity, closed-loop	0.1%
Bidirectional repeatability	50 nm
Rotation (X, Y) typ.	15 µrad / 100 µm
Step and Settle (200 nm), typ.	20 ms
Max. velocity	10 mm/s*
Mechanical properties	
Stiffness in motion direction	0.5 N/µm
Max. push / pull force (active)	10 N
Drive properties	
Drive type	NEXACT® linear drive
Operating voltage	-10 V to +45 V
Miscellaneous	
Operating temperature range	0 to 50°C
Material	Aluminium
Mass	440 g
Cable length	1.5 m
Connector	HD sub-D connector, 15-pin
Recommended controller	E-861.1A1 Controller for NEXACT® Linear Drives and Positioners

* With E-861. Depending on drive electronics.

P-721 PIFOC® Piezo Flexure Objective Scanner

Fast Nanopositioner and Scanner for Microscope Objectives

P-721.CLQ piezo objective nanopositioning system with P-721.12Q QuickLock option and objective (adapter and objective not included)

- **Scans and Positions Objectives with Sub-nm Resolution**
- **Travel Ranges to 140 µm, Millisecond Settling Time**
- **Significantly Faster Response and Higher Lifetime than Motorized Z-Stages**
- **Parallel Precision Flexure Guiding for Better Focus Stability**
- **Choice of Position Sensors: Capacitive Direct Metrology (Higher Performance) or Strain Gauge (Lower Cost)**
- **Compatible with Metamorph™ Imaging Software**
- **Outstanding Lifetime Due to PICMA® Piezo Actuators**
- **QuickLock Adapter for Easy Attachment**
- **Clear Aperture up to 29 mm Ø**

P-721 PIFOCs® are high-speed, piezo-driven microscope objective nanofocusing/scanning devices, providing a positioning and scanning range of 100 µm with sub-nanometer resolution and very high motion of linearity up to 0.03 %. For applications, such as the two-photon spectroscopy wich requires a particulary high resolution, there are versions wich allow a free aperture of up to 29 mm in diameter.
PIFOCs® are also available with up to 460 µm travel (P-725 p. 2-28), and for exceptional dynamic and step performance (models P-726 p. 2-32 and P-725.SDD p. 2-30).

Application Examples

- 3D-Imaging
- Z Stack Acquisition
- Screening
- Interferometry
- Metrology
- Disc-drive-testing
- Autofocus systems
- Confocal microscopy
- Biotechnology
- Semiconductor testing

Superior Accuracy With Direct-Metrology Capacitive Sensors

Capacitive position feedback is used in the top-of-the-line models. PI's proprietary capacitive sensors measure position directly and without physical contact. They are free of friction and hysteresis, a fact which, in combination with the positioning resolution of well under 1 nm, makes it possible to achieve very high levels of linearity. A further advantage of direct metrology with capacitive sensors is the high phase fidelity and the high bandwidth of up to 10 kHz.
Alternatively, strain gauge sensor (SGS) models are available. The sensors are connected in a bridge configuration to eliminate thermal drift, and assure optimal position stability in the nanometer range.

Open-loop models are available for applications where fast response and very high resolution are essential. Here, specifying or reporting absolute position values is either not required or is handled by external sensors, such as interferometers, a vision system or photodiode PSD (position sensitive detector). These models retain the inherent piezo advantages such as high resolution and speed.

Ordering Information

P-721.CDQ
Fast PIFOC® Piezo Nanofocusing Z-Drive, 100 µm, Direct Metrology, Capacitive Sensor, Sub-D Connector, for Quick Lock Thread Adapters

P-721.CLQ
Fast PIFOC® Piezo Nanofocusing Z-Drive, 100 µm, Direct Metrology, Capacitive Sensor, LEMO Connector, for Quick Lock Thread Adapters

P-721.SL2
Fast PIFOC® Piezo Nanofocusing Z-Drive, 100 µm, SGS-Sensor, LEMO Connector, for Quick Lock Thread Adapters

P-721.0LQ
Fast PIFOC® Piezo Nanofocusing Z-Drive, 100 µm, No Sensor, LEMO Connector, for Quick Lock Thread Adapters

P-721.CDA
Fast PIFOC® Piezo Nanofocusing Z-Drive, 100 µm, Direct Metrology, Capacitive Sensor, Sub-D Connectors, for Large Aperture QuickLock Thread Adapters

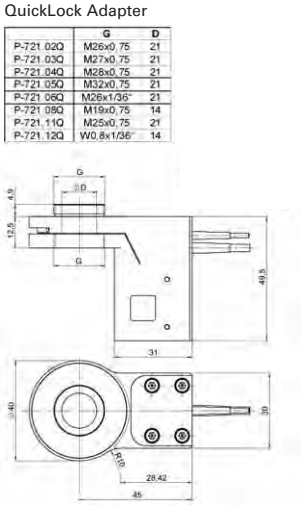
P-721.SDA
Fast PIFOC® Piezo Nanofocusing Z-Drive, 100 µm, SGS Sensor, Sub-D Connectors, for Large Aperture QuickLock Thread Adapters

Accessories

QuickLock Thread Adapter, Large Aperture QuickLock Thread Adapter s. fig.; Extension Tubes for Objectives s. www.pi.ws

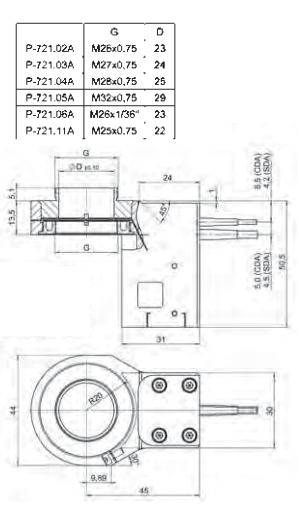
QuickLock Adapter

	G	D
P-721.02Q	M26x0.75	21
P-721.03Q	M27x0.75	21
P-721.04Q	M28x0.75	21
P-721.05Q	M32x0.75	21
P-721.06Q	M26x1/36"	21
P-721.08Q	M19x0.75	14
P-721.11Q	M25x0.75	21
P-721.12Q	W0.8x1/36"	14



P-721.xxQ, .SL2 dimensions in mm (adapter to be ordered separately)

	G	D
P-721.02A	M26x0.75	23
P-721.03A	M27x0.75	24
P-721.04A	M28x0.75	25
P-721.05A	M32x0.75	29
P-721.06A	M26x1/36"	23
P-721.11A	M25x0.75	22



P-721.CDA, .SDA, dimensions in mm (adapter to be ordered separately)

Simple Installation with QuickLock Thread Options

The PIFOC® is mounted between the turret and the objective with the QuickLock thread adapter. After threading the adapter into the turret, the QuickLock is affixed in the desired position. Because the PIFOC® body need not to be rotated, cable wind-up is not an issue.

High Reliability and Long Lifetime

The compact PIFOC® systems are equipped with preloaded PICMA® high-performance piezo actuators which are integrated into a sophisticated, FEA-modeled, flexure guiding system. The PICMA® actuators feature cofired ceramic encapsulation and thus offer better performance and reliability than conventional piezo actuators. Actuators, guidance and sensors are maintenance-free and not subject to wear, and thus offer an extraordinary reliability.

Choice of Controllers

A large choice of analog and digital piezo controllers as OEM, bench-top and 19-inch-rack-mount versions is available.

Technical Data

Model	P-721.CLQ	P-721.CDQ P-721.CDA	P-721.SL2 P-721.SDA	P-721.0LQ	Units	Tolerance
Active axes	Z	Z	Z	Z		
Motion and positioning						
Integrated sensor	Capacitive	Capacitive	SGS	–		
Open-loop travel, -20 to +120 V	140	140	140	140	µm	min. (+20 %/-0%)
Closed-loop travel	100	100	100	–	µm	calibrated
Open-loop resolution	0.5	0.5	0.5	0.5	nm	typ.
Closed-loop resolution	0.7	0.7	5	–	nm	typ.
Linearity, closed-loop	0.03	0.03	0.2	–	%	typ.
Repeatability	±5	±5	±10	–	nm	typ.
Runout θX, θY	13	13	13	13	µrad	typ.
Crosstalk X, Y	100	100	100	100	nm	typ.
Mechanical properties						
Stiffness in motion direction	0.3	0.3	0.3	0.3	N/µm	±20 %
Unloaded resonant frequency	580	580	580	550	Hz	±20 %
Resonant frequency @ 120 g	235	235	235	235	Hz	±20 %
Resonant frequency @ 200 g	180	180	180	180	Hz	±20 %
Push/pull force capacity in motion direction	100 / 20	100 / 20	100 / 20	100 / 20	N	Max.
Drive properties						
Ceramic type	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885		
Electrical capacitance	3.1	3.1	3.1	3.1	µF	±20 %
Dynamic operating current coefficient	3.9	3.9	3.9	3.9	µA/(Hz•µm)	±20 %
Miscellaneous						
Operating temperature range	-20 to 80	-20 to 80	-20 to 80	-20 to 80	°C	
Material	Aluminum	Aluminum	Aluminum	Aluminum		
Mass	0.24	0.24	0.22	0.22	kg	±5 %
Max. objective diameter	39	39	39	39	mm	
Cable length	1	1	1	1	m	±10 mm
Sensor / voltage connection	LEMO	Sub-D Special	LEMO/Sub-D Special	LEMO (no sensor)		
Recommended controller / amplifier	E-610 servo controller/amplifier (p. 2-110), modular piezo controller system E-500 (p. 2-142) with amplifier module E-505 (high performance) (p. 2-147) and E-509 servo controller (p. 2-152)	E-625 servo controller, bench top (p. 2-114), E-665 powerful servo controller, bench-top (p. 2-116), Single-channel digital controller: E-753 (bench-top) (p. 2-108) E-709 single-channel digital controller	SL2 version: E-610 servo controller/amplifier, E-625 servo controller, bench-top, E-665 powerful servo controller, bench-top SDA version: E-709 single-channel digital controller	E-610 servo controller/amplifier		

Resolution of PI Piezo Nanopositioners is not limited by friction or stiction. Value given is noise equivalent motion with E-503 amplifier (p. 2-144)

PIMars 6-Axis Piezo Stage

High-Precision Nanopositioning System with 6 Degrees of Freedom

P-562.6CD PIMars six-axis parallel-kinematics nanopositioning stage

- **6 Motion Axes: 3 x Linear, 3 x Rotation**
- **Travel Ranges to 200 µm Linear and 1 mrad Tilt Angle**
- **Enhanced Responsiveness & Multi-Axis Precision: Parallel Kinematics / Metrology**
- **Highest Linearity and Stability with Capacitive Sensors**
- **Frictionless, High-Precision Flexure Guiding System**
- **Excellent Scan-Flatness**
- **Clear Aperture 66 x 66 mm**
- **Outstanding Lifetime Due to PICMA® Piezo Actuators**
- **UHV Versions to 10^{-9} hPa**

PIMars open-frame piezo stages are fast and highly accurate multi-axis scanning and nanopositioning systems with flatness and straightness in the nanometer range. Thanks to the parallel-kinematic design, where all piezo drives act on the same moving platform, and sophisticated digital control algorithms it is possible to achieve highly precise motion in all degrees of freedom: three linear axes and three rotary axes. The travel ranges amount to 200 µm in X, Y and Z, and the tilt angles are ±0.5 mrad about the respective axis. Systems with larger travel ranges or faster response are available on request. A six-axis system with 800 µm travel range in the X and Y axis is available as the P-587.6CD s. p. 2-76.

PIMars systems feature a large 66 x 66 mm clear aperture for transmitted-light applications such as near-field scanning or confocal microscopy and mask positioning. PIMars stages for ultra-high vacuum applications are also available. These versions contain vacuum-qualified components only. The integrated ceramic-encapsulated PICMA® actuators allow high bakeout temperatures and assure minimal outgassing rates. A non-magnetizable version is available on request.

Application Examples

- Scanning microscopy (SPM)
- Mask/wafer positioning
- Interferometry
- Metrology
- Biotechnology
- Micromanipulation

Ordering Information

P-562.6CD
PIMars 6-Axis Nanopositioning System, 200 µm, 1 mrad, Parallel Metrology

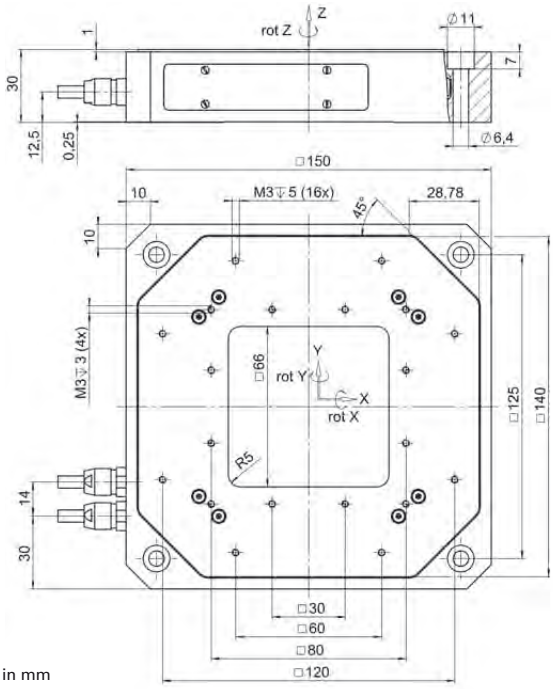
Other travel ranges on request!

Capacitive Sensors for Highest Accuracy and Stability

PI's proprietary capacitive sensors measure position directly and without physical contact. They are free of friction and hysteresis, a fact which, in combination with the positioning resolution of well under 1 nm, makes it possible to achieve very high levels of linearity. Further advantages of direct metrology with capacitive sensors are the excellent long-term stability, high phase fidelity and the high bandwidth of up to 10 kHz.

Active and Passive Guidance for Nanometer Flatness and Straightness

Wire-cut flexures optimized with Finite Element Analysis (FEA) are used to guide the stage. The FEA techniques give the design the highest possible stiffness and minimize linear and angular run-out. Further enhancement is achieved by active trajectory control: multiaxis nanopositioning systems equipped with parallel metrology are able to measure platform position in all degrees of freedom against a common, fixed reference. In such systems, undesirable motion from one actuator in the direction of another (cross-talk) is detected immediately and actively compensated by the servo-loops. This can keep deviation from a trajectory to under a few nanometers, even in dynamic operation.



P-562 dimensions in mm

E-712 Modular Digital Multi-Channel Piezo Controller

Technical Data

Model	P-562.6CD	Tolerance
Active axes	X, Y, Z, θX, θY, θZ	
Motion and Positioning		
Integrated sensor	Capacitive	
Closed-loop travel X, Y, Z	200 µm	
Closed-loop tip/tilt angle	±0.5 mrad	
Closed-loop resolution X, Y, Z	1 nm	typ.
Closed-loop tip/tilt resolution	0.1 µrad	typ.
Linearity X, Y, Z	0.01 %	typ.
Linearity θX, θY, θZ	0.1 %	typ.
Repeatability in X, Y, Z	±2 / ±2 / ±3 nm	typ.
Repeatability θX / θY / θZ	±0.1 / ±0.1 / ±0.15 µrad	typ.
Flatness	< 15 nm	typ.
Unloaded resonant frequency in X / Y / Z	110 / 110 / 190 Hz	±20%
Load capacity	50 N	max.
Push/pull force capacity in motion direction	120 / 30 N	max.
Drive properties		
Ceramic type	PICMA®	
Electrical capacitance in X / Y / Z	7.4 / 7.4 / 14.8 µF	±20%
Dynamic operating current coefficient in X, Y, Z	4.6 / 4.6 / 9.2 µA/(Hz • µm)	±20%
Miscellaneous		
Operating temperature range	-20 to 80 °C	
Material	Aluminium	
Mass	1.45 kg	±5%
Cable length	1.5 m	±10 mm
Sensor / voltage connection	2 x Sub-D Special	

Recommended controller / amplifier
E-710.6CD s. p. 2-128 or E-712.6CD digital controller s. p. 2-140

E-536 PicoCube® Ultra-Low Noise Piezo Controller

High Dynamics, High Resolution, for up to 3 Axes

E-536.3C 3-channel PicoCube® Controller

- **For P-363 PicoCube® Systems**
- **Peak Power 3 x 100 W**
- **Ultra-Low Noise**
- **Output Voltage ±250 V**

The E-536 is a controller for the P-363 PicoCube® pico-positioning system providing three ultra-low-noise amplifier channels for piezo shear actuators. The controller design meets the special requirements of the high-speed, ultra-high-perform - ance PicoCube ® XY(Z) piezo stages (see p. 2-66) of ±250 V for both static and dynamic applications.

The high-performance E-536.3x can output and sink peak currents up to 200 mA featuring a small-signal bandwidth of 10 kHz. The E-536.3xH ultra-high-resolution models provide a position resolution below 0.03 nm at a peak power of 50 W . Both models are available with or without a servo module for closed-loop or open-loop operation.

Superior Resolution and High Dynamics

Open-loop operation is ideal for applications where fast response and very high resolution with maximum bandwith are essential. Here, commanding and reading the traget position in absolute values is either not important or carried out by external position sensors. Together with the P-363 PicoCube® a resolution of 0.05 nm or better is achieved.

Excellent Position Accuracy with Capacitive Sensors

The E-536.3C versions have integrated sensor electronics and servo-controllers for closed-loop position control. Position feedback is provided by capacitive sensors, like those in the PicoCube ®, with resolutions down to 0.1 nm.

Computer Control

Control via PC is possible by installing the E-517, 24-bit interface/display module.

Optionally digital control via a D/A converter is possible. For several D/A boards from National Instruments PI offers a corresponding LabVIEW™ driver set which is compatible with the PI General Command Set (GCS), the command set used by all PI controllers. A further option includes the patented Hyperbit™ technology providing enhanced system resolution.

Ordering Information

E-536.3C
PicoCube® Piezo Controller, 3 Channels, Capacitive Sensors

E-536.30
PicoCube® Piezo Controller, 3 Channels, Open-Loop

E-536.3CH
PicoCube® Piezo Controller, 3 Channels, High-Resolution, Capacitive Sensors

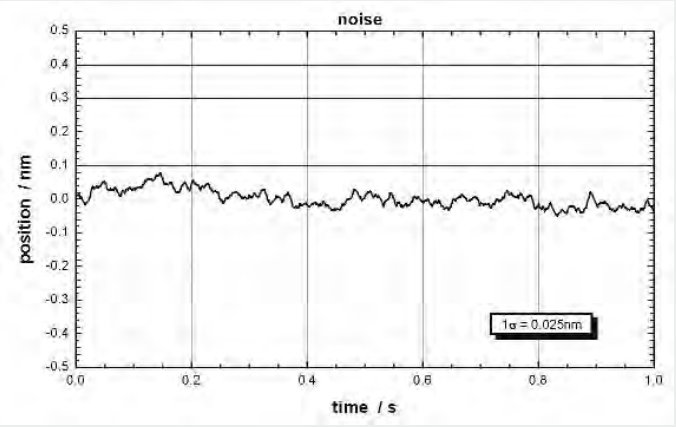
E-536.30H
PicoCube® Piezo Controller, 3 Channels, High-Resolution, Open-Loop

E-517.i3
Interface- / Display Module, 24 Bit D/A, TCP/IP, USB, RS-232, 3 Channels

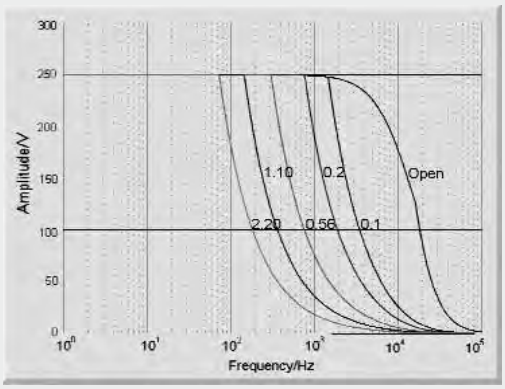
E-500.HCD
Hyperbit™ Functionality for Enhanced System Resolution

(Supports certain D/A boards.)

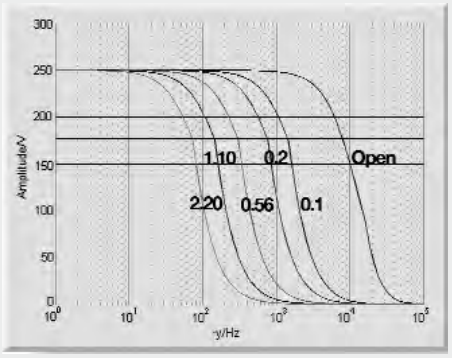
E-536 controller with P-363 PicoCube® pico-positioning system



Positional noise measurement of E-536 amplifier driving a P-363 pico-positioning system in open loop shows 1-sigma resolution of 25 picometers (0.025 nm). Measured with ultra-high-resolution capacitive sensor



E-536.3x: operating limits with various PZT loads, capacitance is measured in µF



E-536.3xH: operating limits with various PZT loads, capacitance is measured in µF

Technical Data

Model	E-536.3C / E-536.30	E-536.3CH / E-536.30H
Function	Power amplifier & servo-controller for P-363 PicoCube®	Power amplifier & servo-controller for P-363 PicoCube®
Amplifier		
Output voltage	-250 to +250 V	-250 to +250 V
Amplifier channels	3	3
Average output power per channel	10 W, limited by temperature sensor	6 W, limited by temperature sensor
Peak output power per channel, <3 ms	100 W	50 W
Average current	30 mA	15 mA
Peak current per channel, <3 ms	200 mA	100 mA
Amplifier bandwidth, small signal	10 kHz	2 kHz
Amplifier bandwidth, large signal, @ 100 nF	0.2 kHz	0.125 kHz
Ripple, noise, 0 to 100 kHz	0.8 mV_{RMS}, <5 mV_{P-P} (100 nF)	0.5 mV_{RMS}, <3 mV_{P-P} (100 nF)
Current limitation	Short-circuit proof	Short-circuit proof
Voltage gain	+50	+50
Input impedance	100 kΩ	100 kΩ
Sensor*		
Servo characteristics	Analog proportional-integral (P-I) algorithm with notch filter	Analog proportional-integral (P-I) algorithm with notch filter
Sensor type	capacitive sensors	capacitive sensors
Sensor channels	3 / -	3 / -
Sensor bandwidth	1.5 kHz	1.5 kHz
Sensor Monitor output	0 to +10 V	0 to +10 V
Interfaces and operation		
PZT output sockets	LEMO EGG.0B.701.CJL.1173	LEMO EGG.0B.701.CJL.1173
Sensor target and probe sockets	LEMO EPL.00.250.NTD	LEMO EPL.00.250.NTD
Control Input sockets	SMB	SMB
Sensor Monitor socket	LEMO FGG.0B.306.CLAD56	LEMO FGG.0B.306.CLAD56
Control Input voltage	Servo off: -5 to +5 V, Servo on: 0 to +10 V	Servo off: -5 to +5 V, Servo on: 0 to +10 V
DC Offset	10-turn pot., adds 0 to +10 V to Control IN	10-turn pot., adds 0 to +10 V to Control IN
Miscellaneous		
Operating voltage	115 VAC / 50-60 Hz or 230 VAC / 50-60 Hz	115 VAC / 50-60 Hz or 230 VAC / 50-60 Hz
Mass	8.1 kg / 7.8 kg (with E-516 module)	8.1 kg / 7.8 kg (with E-516 module)
Dimensions	450 x 132 x 296 mm + handles	450 x 132 x 296 mm + handles

*only E-536.3Cx with capacitive sensors
Interfaces / communication: RS-232, TCP/IP, USB (with optional E-517 computer interface and display module only)
Operating temperature range: +5 °C to +50 °C (over 40 °C, max. av . power derated 10 %), high-voltage output is automatically deactivated if temperature is too high by internal temperature sensor (75 °C max.)

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